

# Introduction to EBSD

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# EBSD

EBSD = Electron Back Scatter Diffraction which allows:

- Crystallographic Orientations
- Misorientations
- Texture measurement
- Grain size and boundary types
- Phases

To be characterised and quantified on a macro to sub-micron or nano-meter scale

## What does EBSD Contribute to Materials Analysis?

- **EDS/WDS - Chemical analysis**
  - i.e. What the sample is made from
- **EBSD - Microstructural analysis**
  - Polycrystalline materials
    - Grain Structure - size/distribution, ASTM number etc.
    - Grain Boundary Characteristics
    - Macro & Micro-Crystallographic Texture
    - Phase Discrimination and distribution
    - Deformation
  - Single Crystal materials/deposited layers
    - Crystal orientation
    - Epitaxy between layers
  - i.e. How the sample is put together and what condition it is in

# Typical Applications

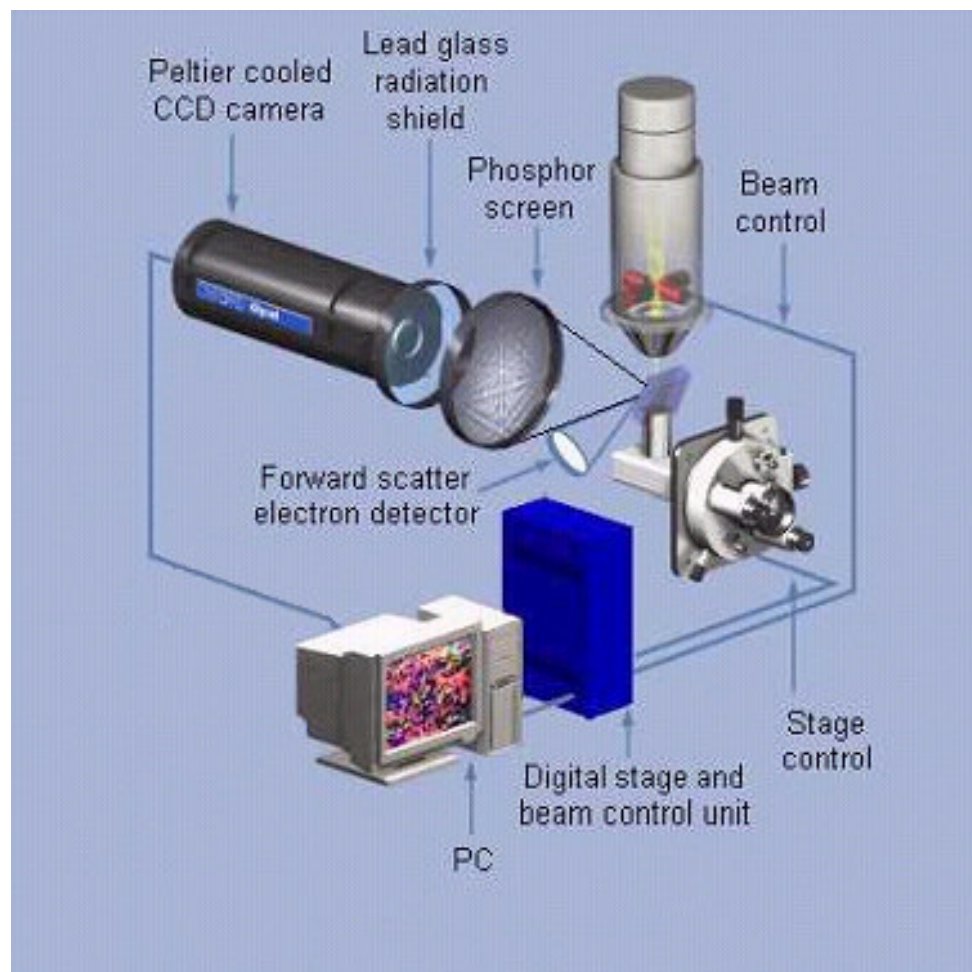
- Metals
  - Metal production i.e. sheet metal, castings, forgings - automotive, aerospace, power generation and distribution, petrochemical and chemical plant, nuclear i.e. extreme duty materials - high strength, high temperature and corrosive environments. Electronics.
  - Phase identification and discrimination
  - Texture analysis, grain boundary characterisation
  - Deformation
- Geological
  - Phase identification and discrimination
  - Orientation & texture analysis
- Ceramics
  - Phase identification and discrimination
  - Orientation & texture analysis



# Typical Areas of Investigation

- Production and process control
  - Cost savings - reduce heat treatment times, optimise heat treatment and phase transformation, investigate grain size, grain boundary and texture evolution
  - Improved product i.e. surface finish, forming or joining characteristics, process optimisation & control
  - Control physical properties - improve or achieve specific properties i.e. high corrosion resistance, fatigue or cracking (stress corrosion cracking) resistance.
- Component life-time prediction
  - Characterise microstructure - identify problem phases or microstructural feature
- Failure Analysis
  - Investigate microstructural features associated with failure and propose failure mechanism

## Schematic Layout of EBSD System



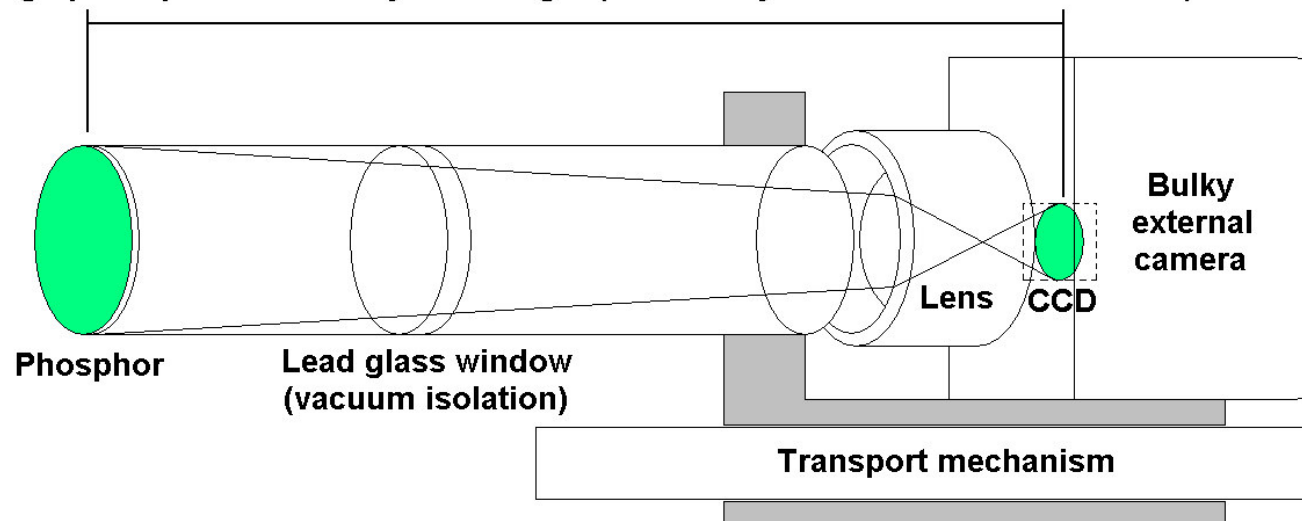
- Schematic layout of components
- PC and Imaging hardware common for INCA Energy and Wave
- Market leading EBSD, EDS & WDS all from one vendor

# 'Nordlys' EBSD Detector



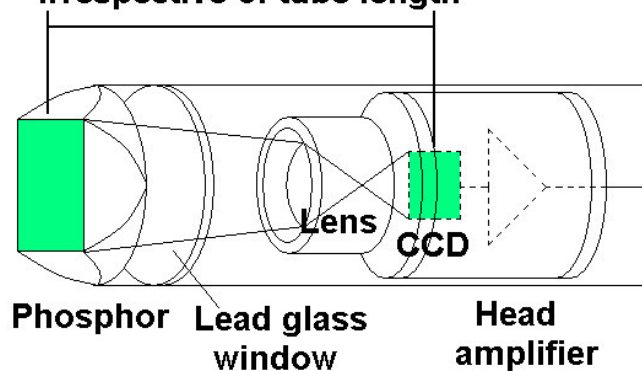
## Comparison of conventional and advanced EBSD hardware design

Long optical path dictated by tube length (dictated by SEM chamber dimensions)



**Conventional  
'open bracket'  
design**

Optimum optical path  
irrespective of tube length



Tube length  
does not  
affect  
efficiency

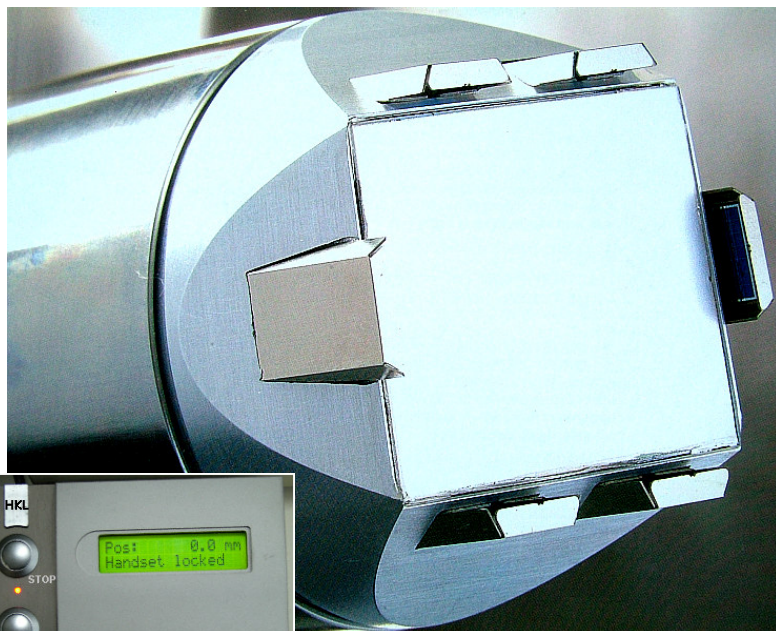
**Advanced 'in tube' design**

Non-essential electronics  
and power supplies remote  
from EBSD hardware

Enclosed transport mechanism

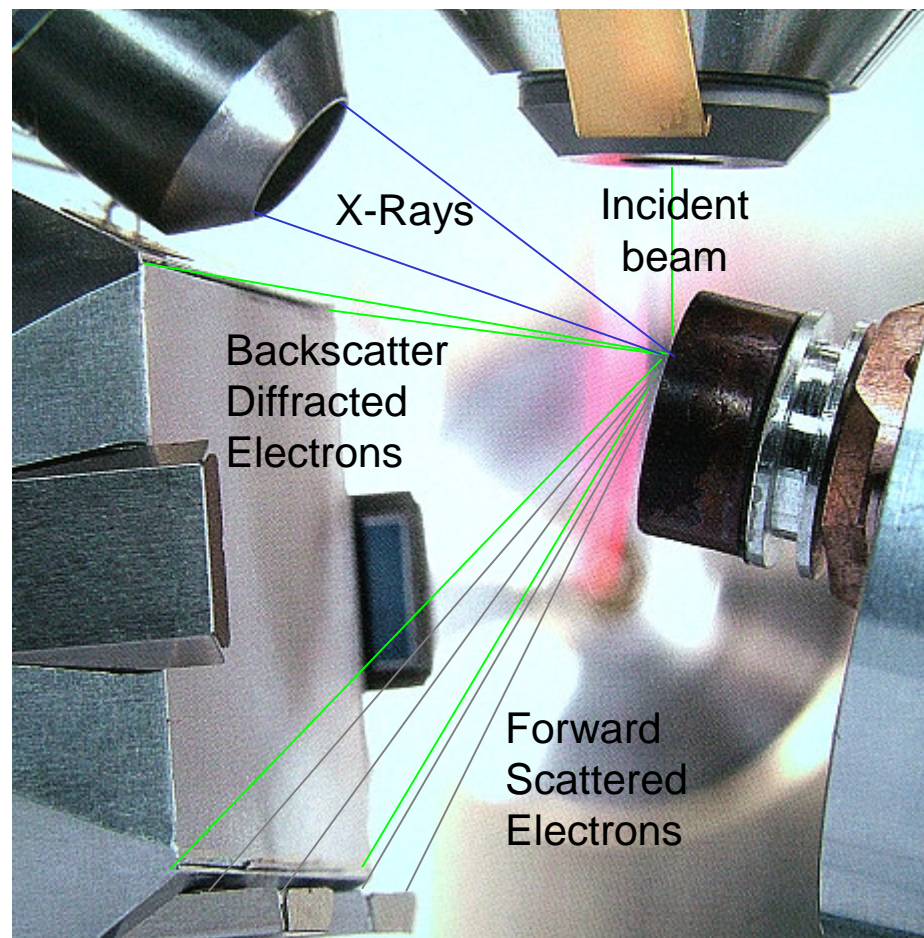


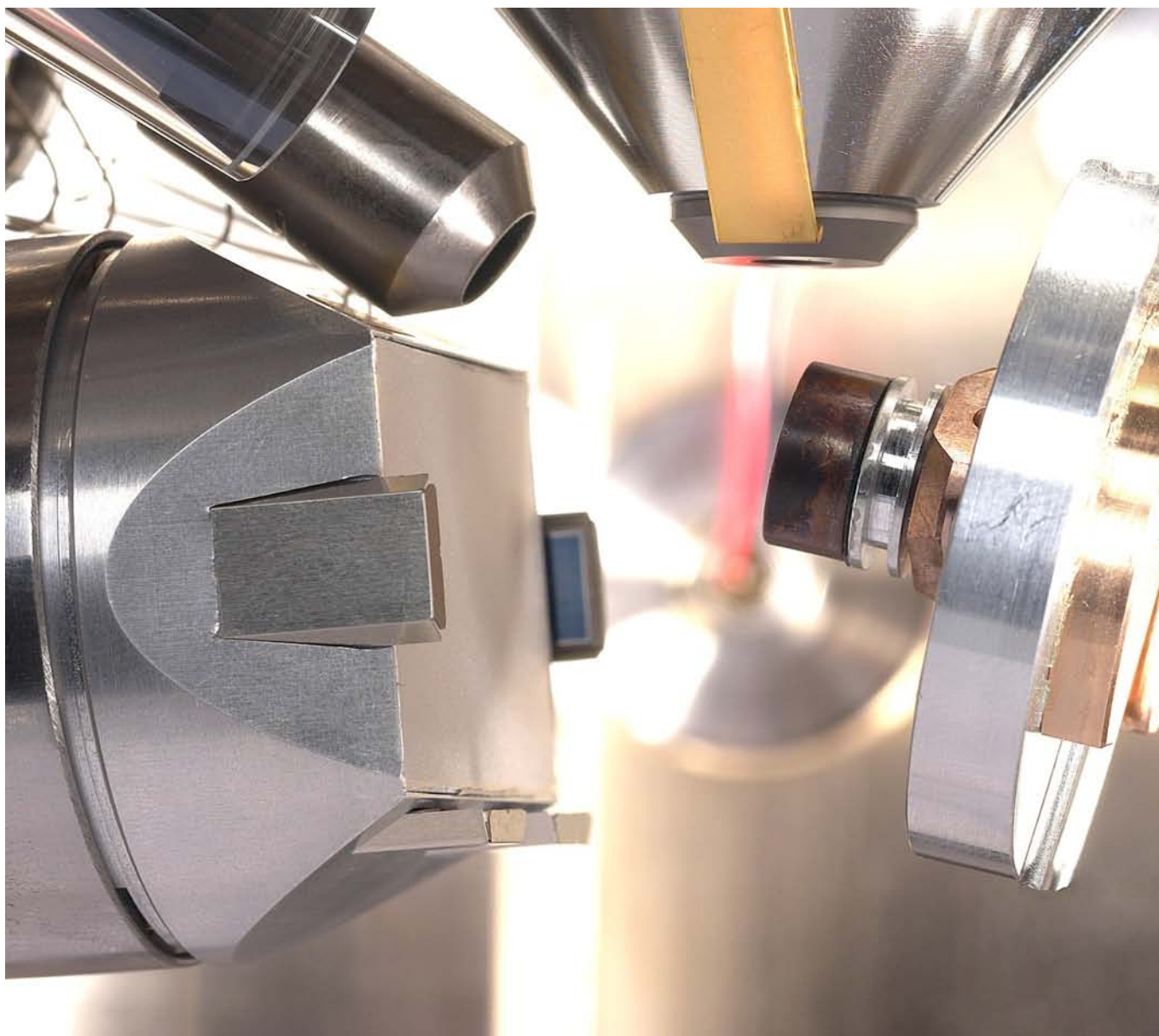
## EBSD hardware - configurable collection geometry



Camera position control unit

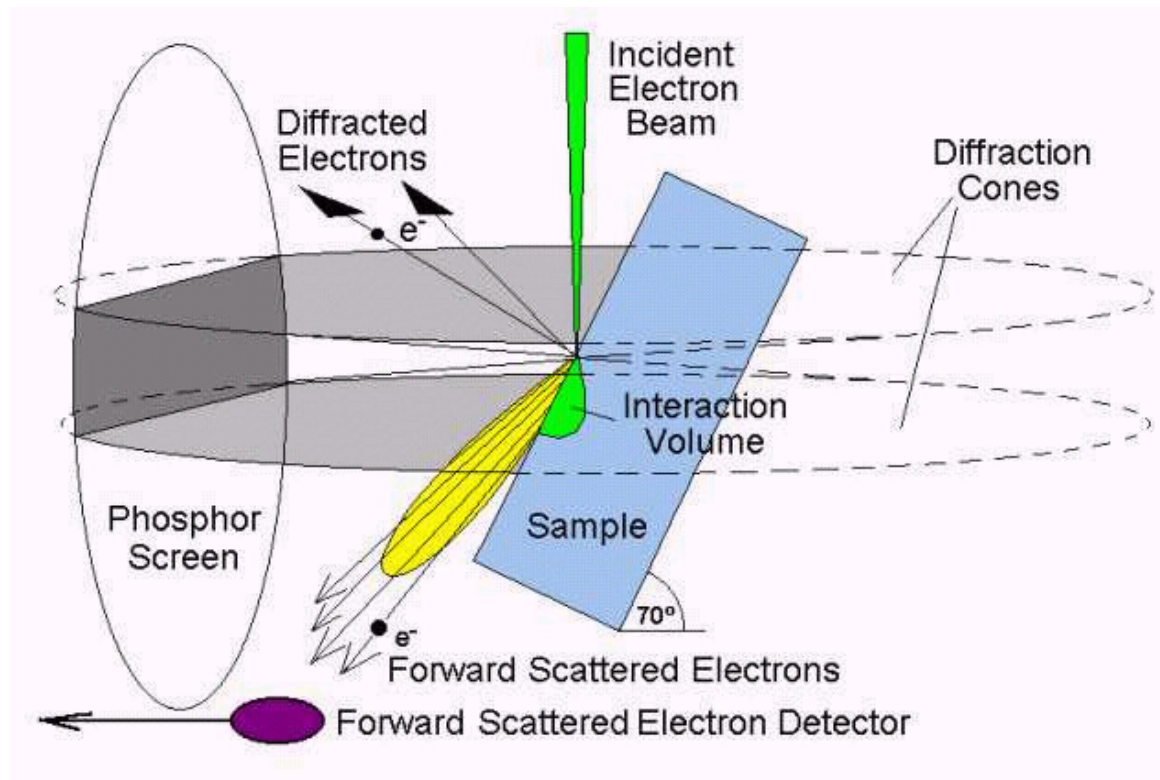
- Revolutionary high efficiency, fast detector with rectangular phosphor and multiple FSE detectors
- Motorized insertion/retraction with no constraints on working geometry
- Can be optimised for short WD or to avoid occluding other detectors





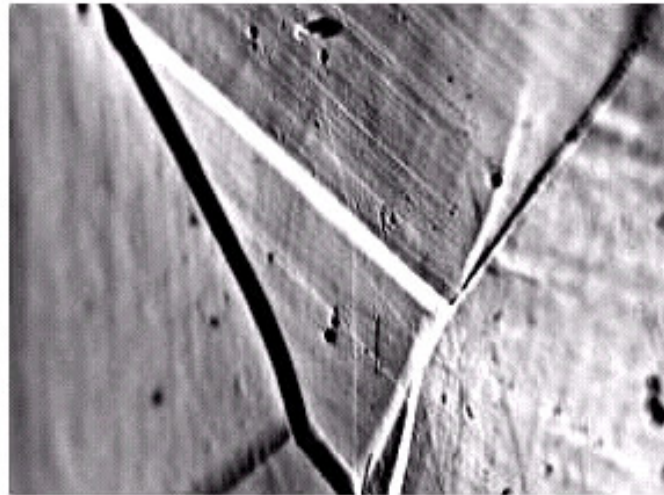


# Forward Scattered Electron (FSE) Imaging

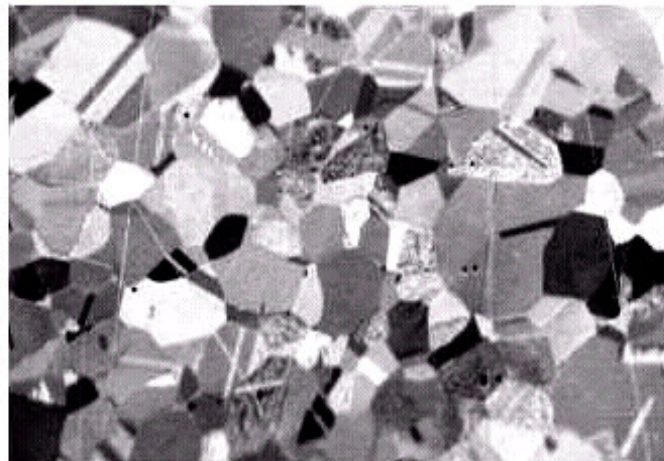
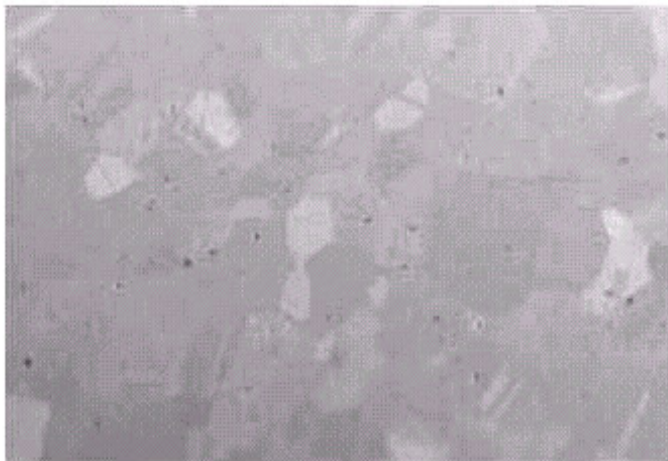


- FSE greatly enhances diffraction contrast in imaging
- Grains and grain boundaries are clearly revealed

# FSE Imaging using a single detector



- Nickel



- Austenitic  
Stainless  
Steel

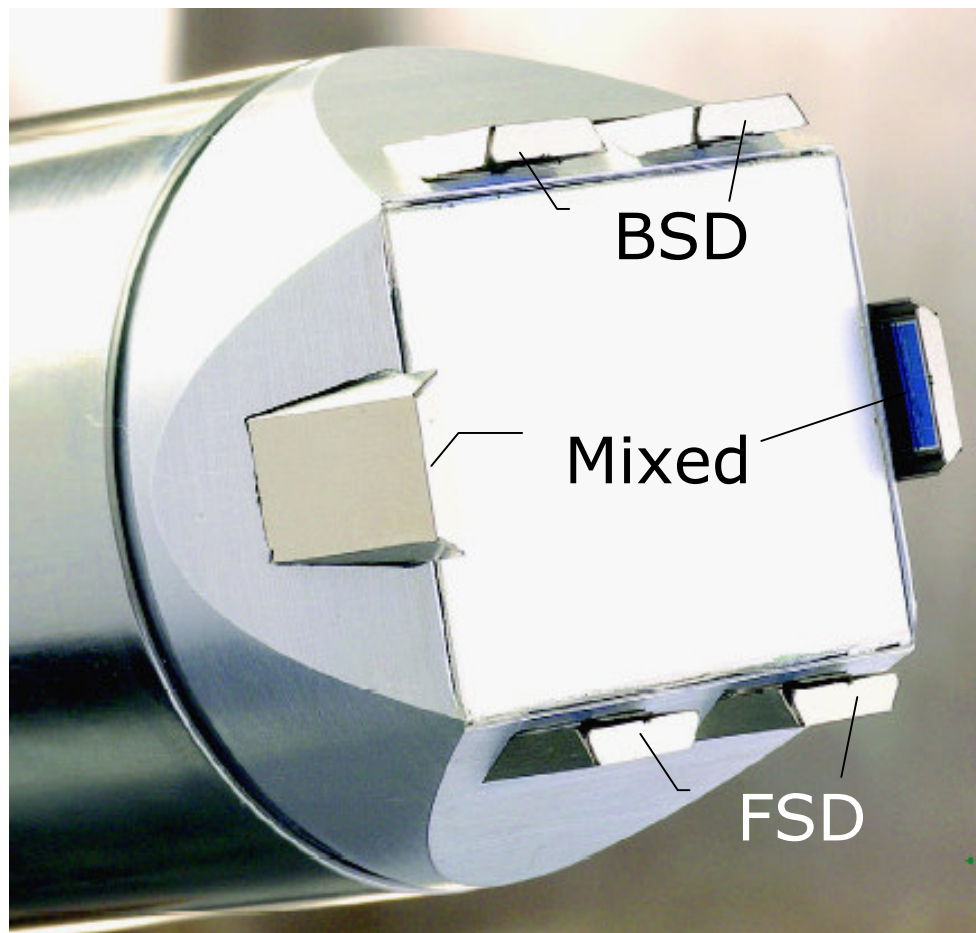
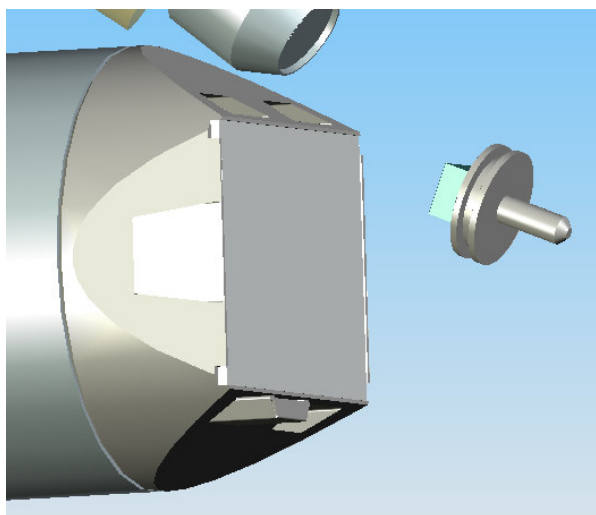
Secondary Electron Image

Forward Scattered Electron Image



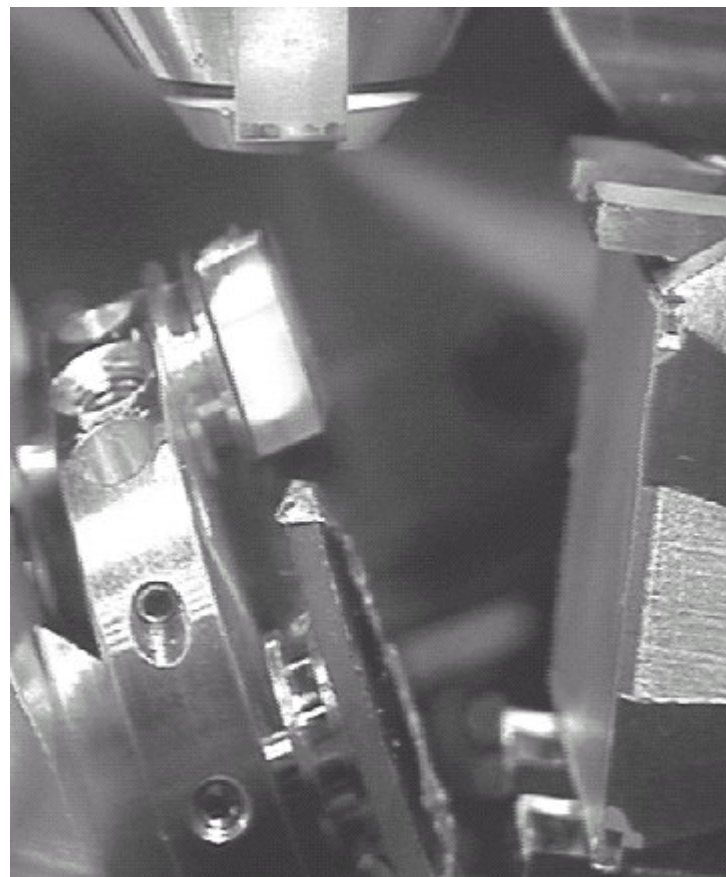
## Forescatter Detector Option

- For orientation, phase contrast imaging at high tilt
- Two, four or six diodes – may be retrofitted or moved by user
- BSE, FSE or mixed mode detection



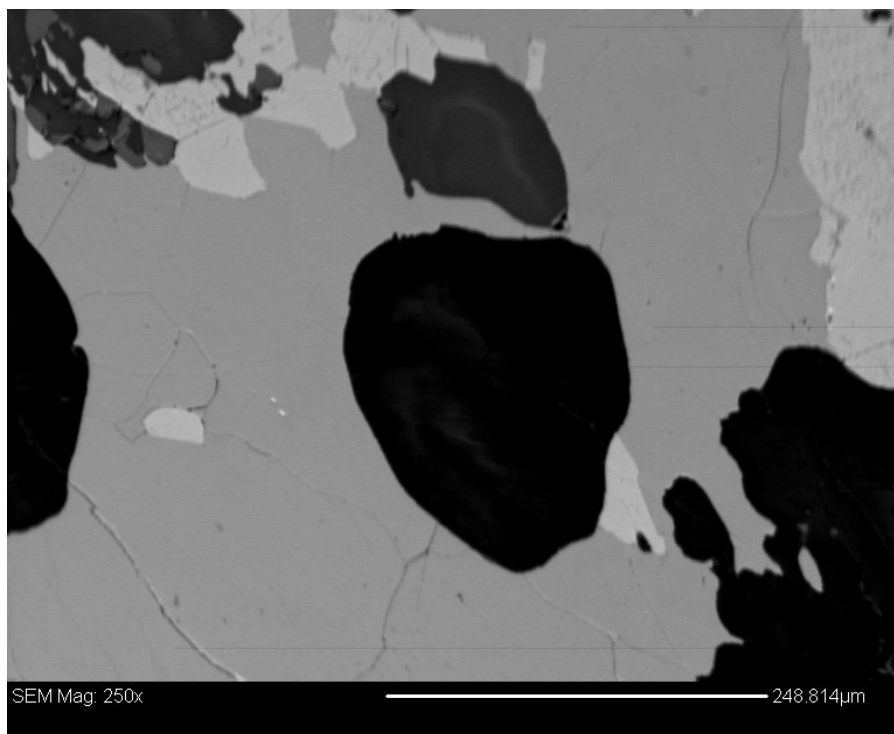
# Multiple Forescatter Detector Option

Diode orientation and position optimal for high tilt EBSD conditions

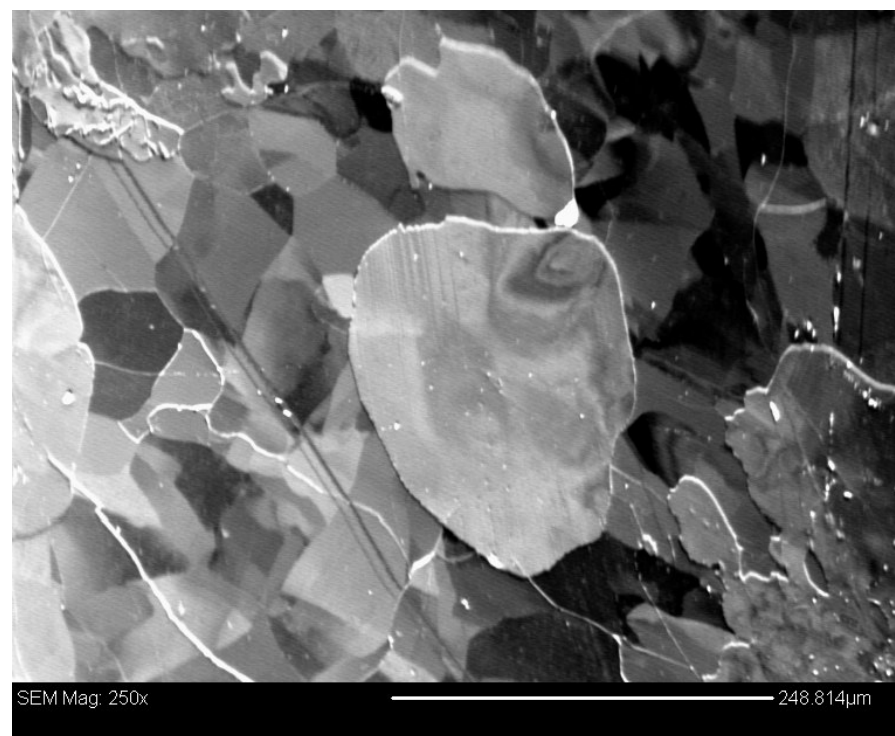


# Forescatter Detector: Orientation Contrast & Phase Contrast

Multiphase rock (gabbro)



BSE Image – Density (phase)  
contrast

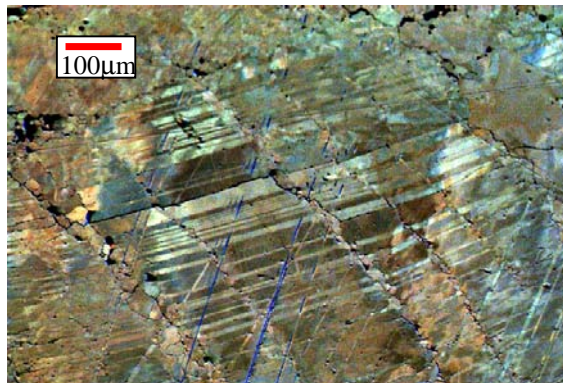


OC (FSD) Image – Channeling contrast

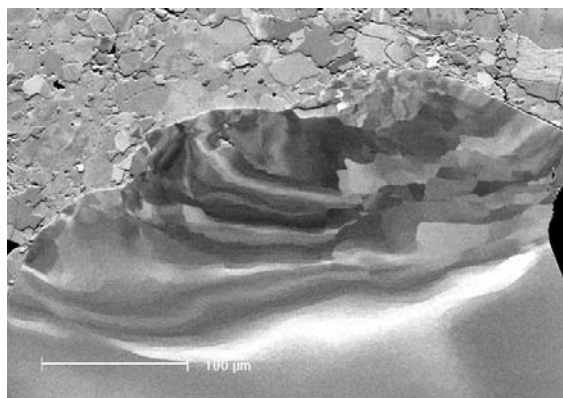
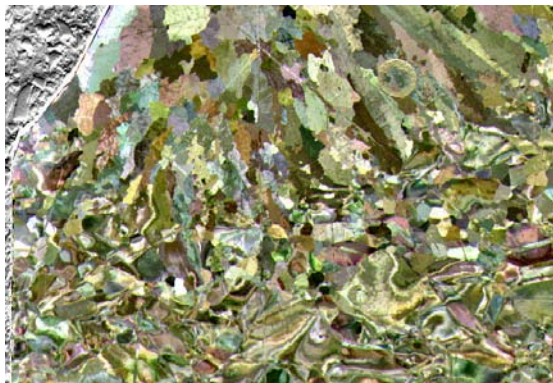


# Forescatter gallery

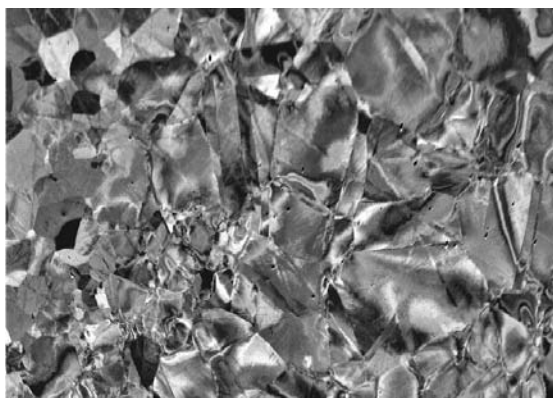
Calcite (Dave Prior, Liverpool)



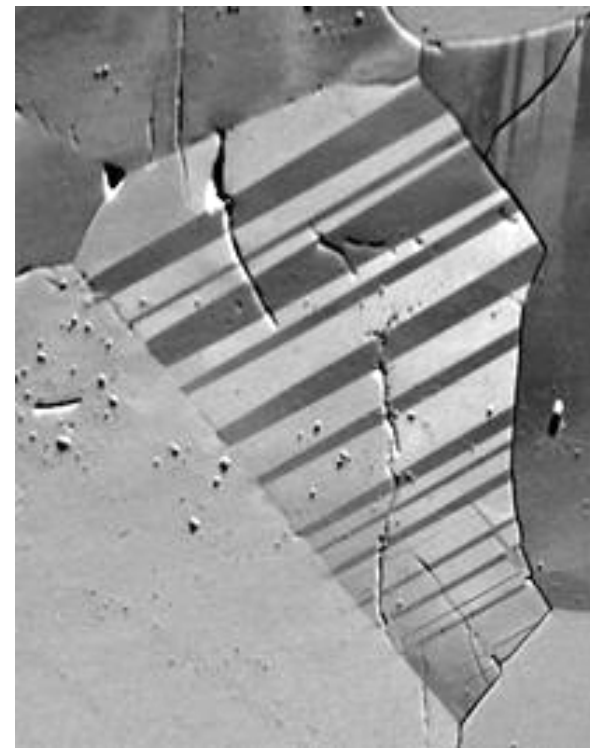
Welded superalloy (NPL)



Zircon grain



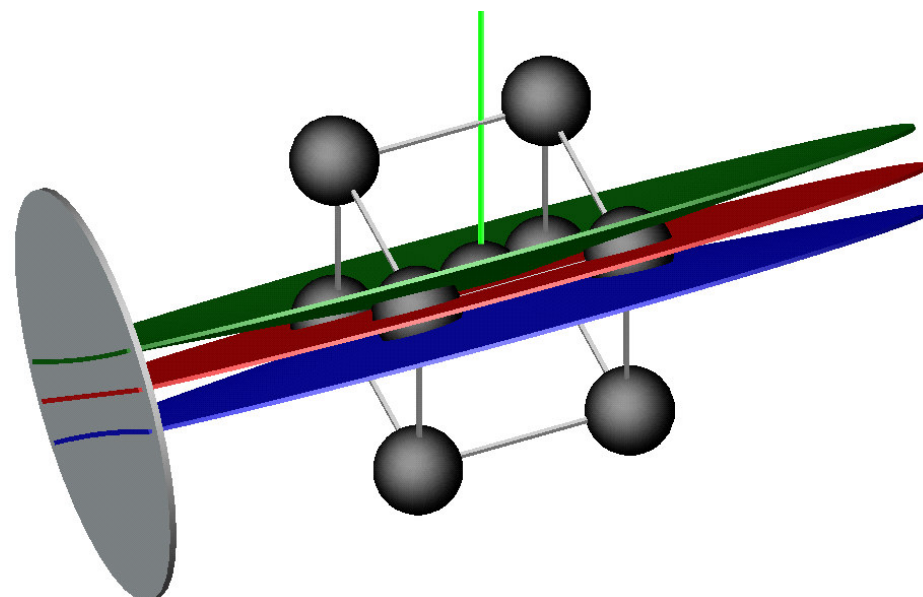
Deformed superalloy



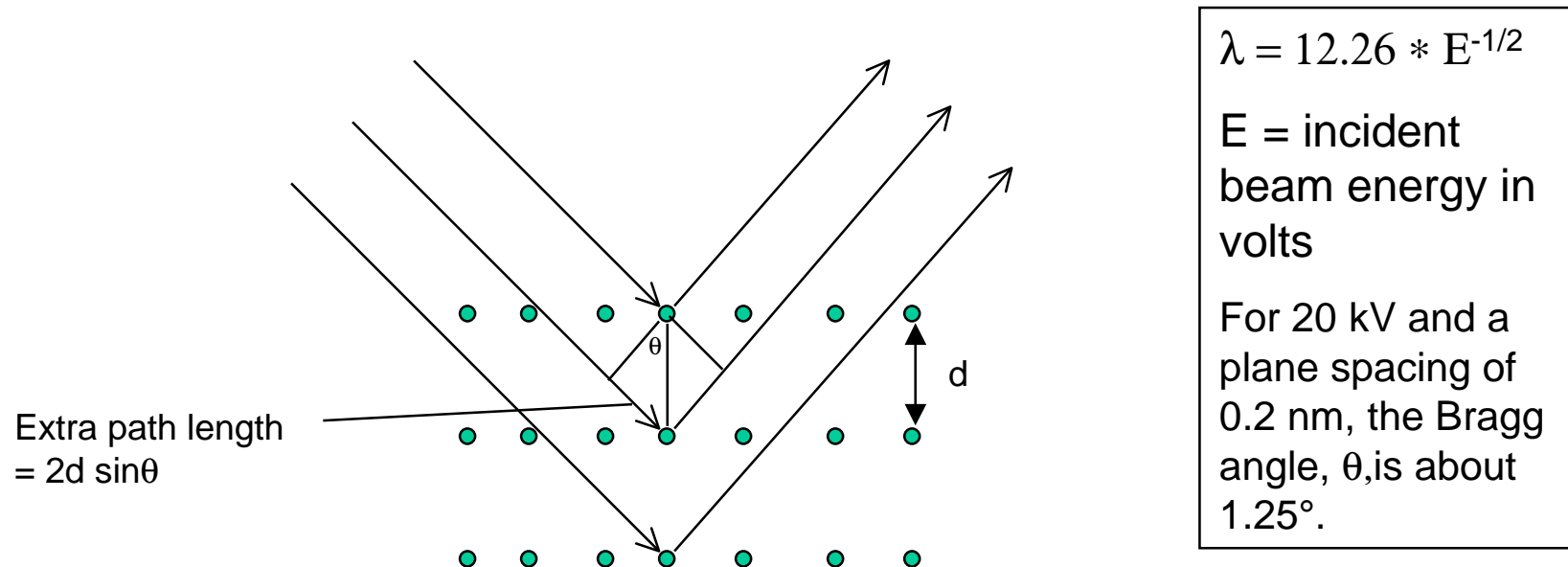
Plagioclase

# EBSP Formation

- The electron beam strikes the specimen
- Scattering produces backscatter electrons in all directions, most intensely downward & outward
- Electrons that travel along a crystallographic plane trace generate **Kikuchi bands** whose widths are dictated by the Bragg Law and specimen-to-phosphor screen distance.
- The electrons hit the imaging phosphor and produce light
- The light is detected by a CCD/SIT camera and converted to an image
- Which is indexed...



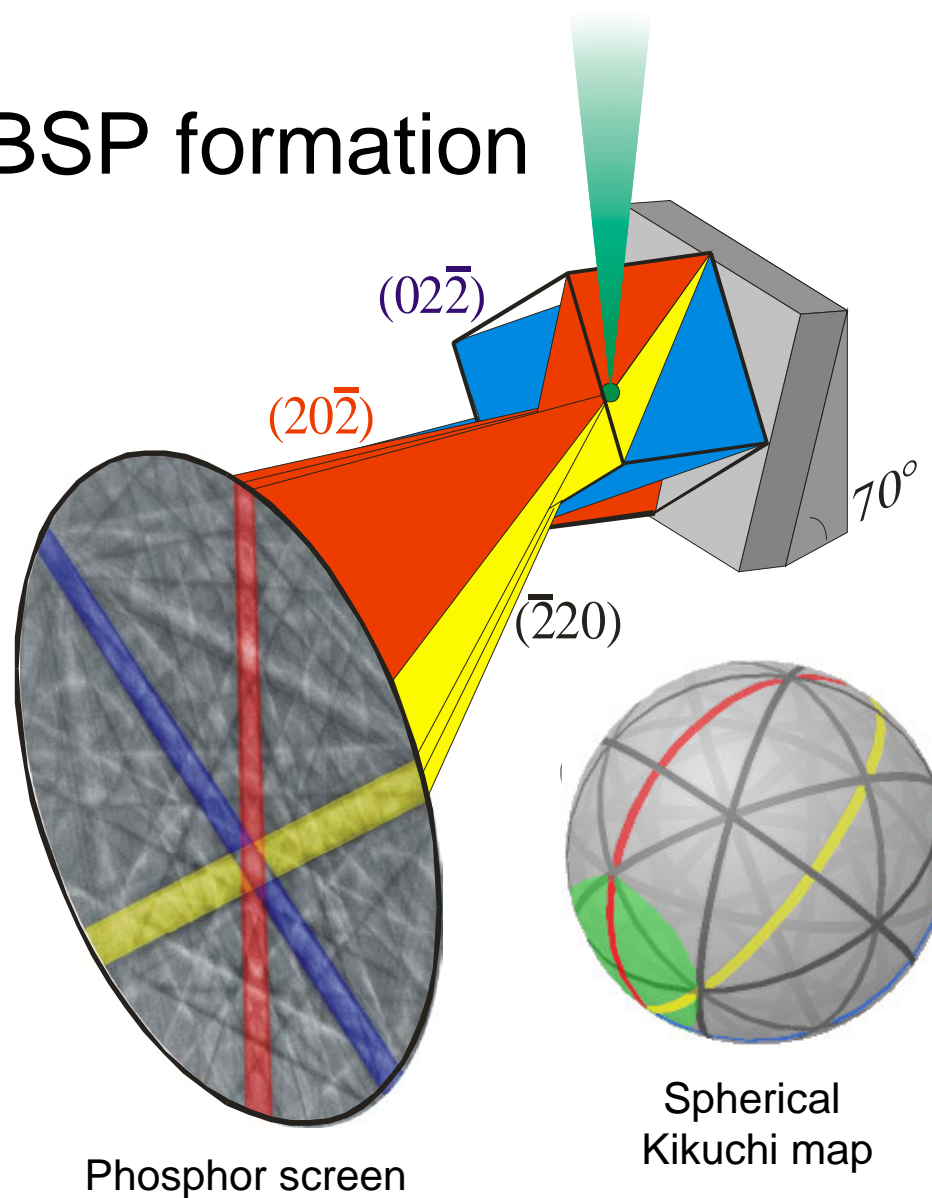
# Diffraction



Constructive interference occurs when the extra path length is an integral number of wavelengths.

$$\text{Bragg's Law } n\lambda = 2d \sin\theta$$

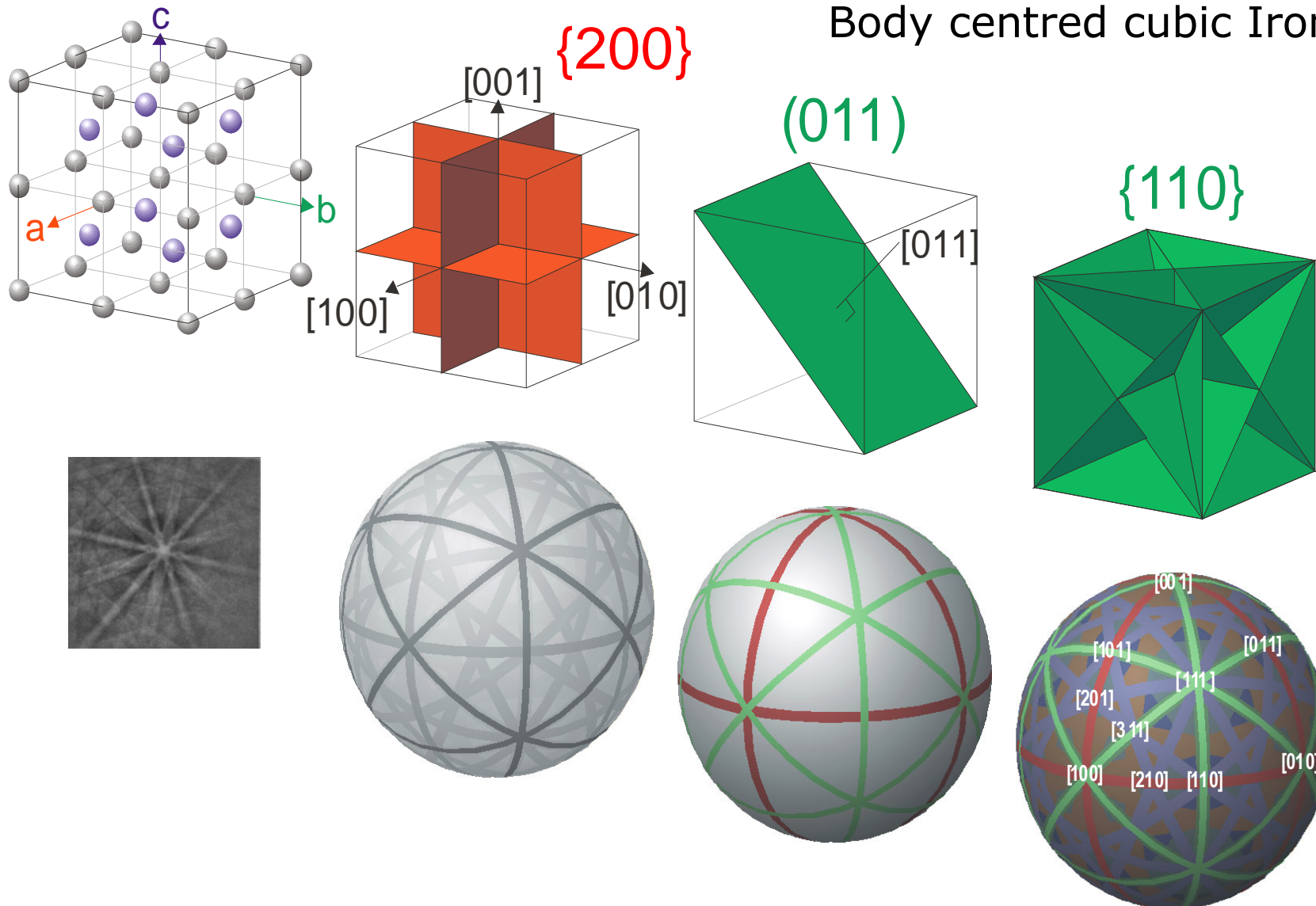
# EBSP formation





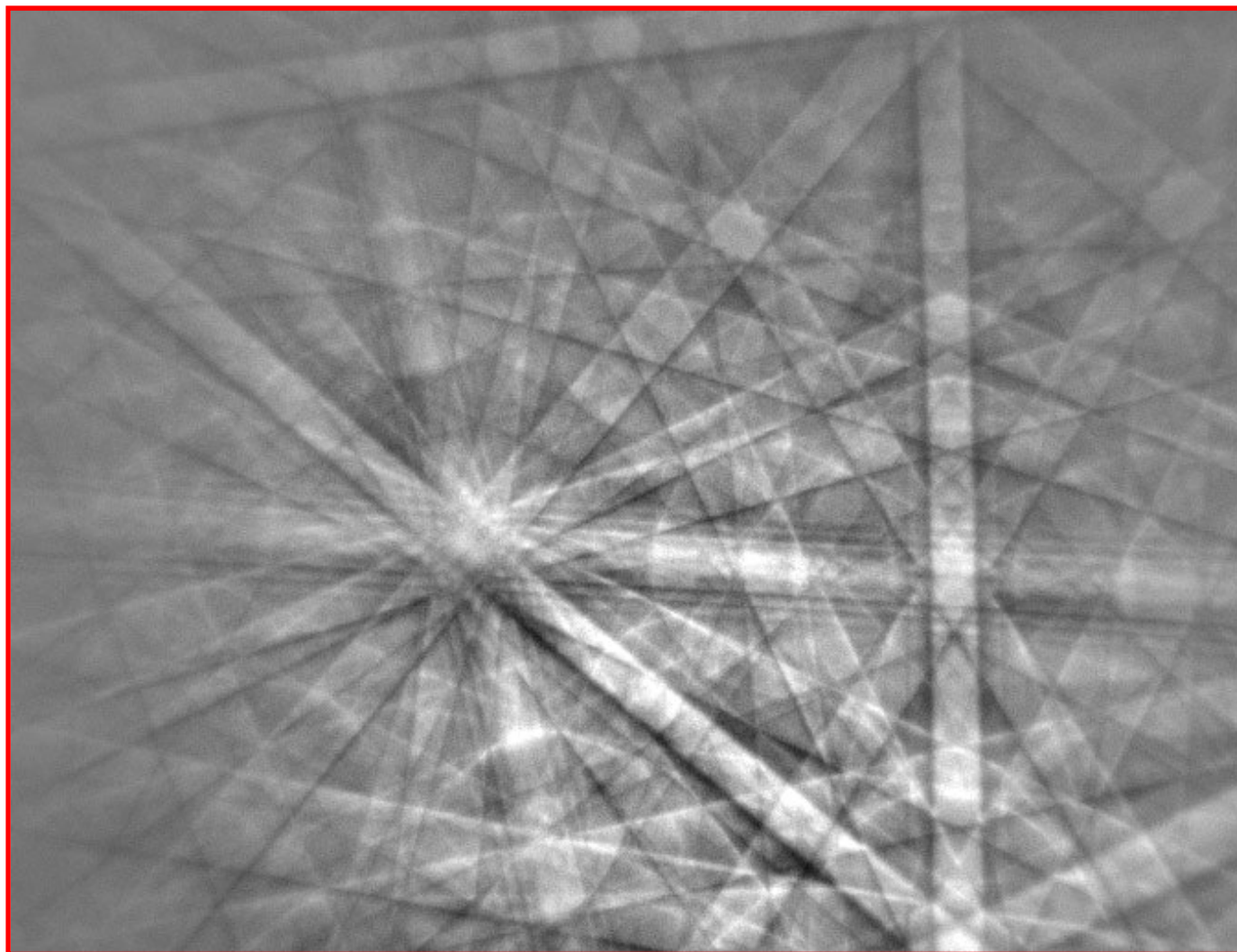
# EBSP formation

Body centred cubic Iron



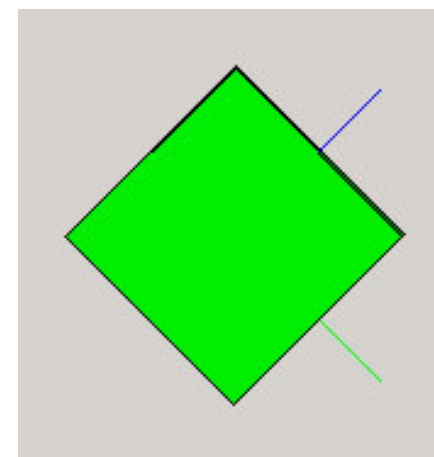
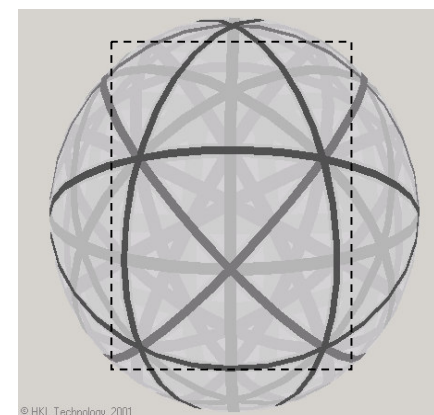
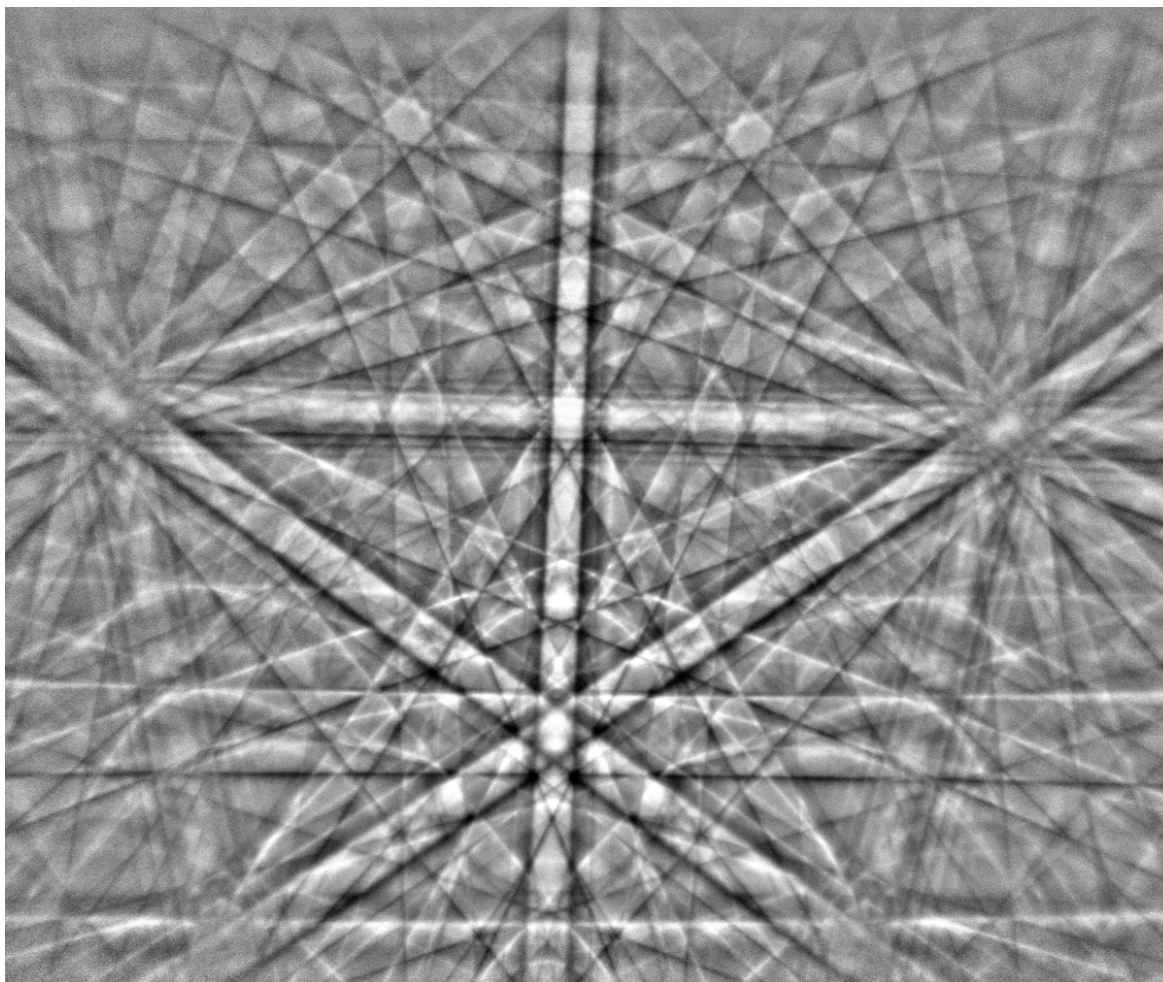


## What does an EBSD look like?

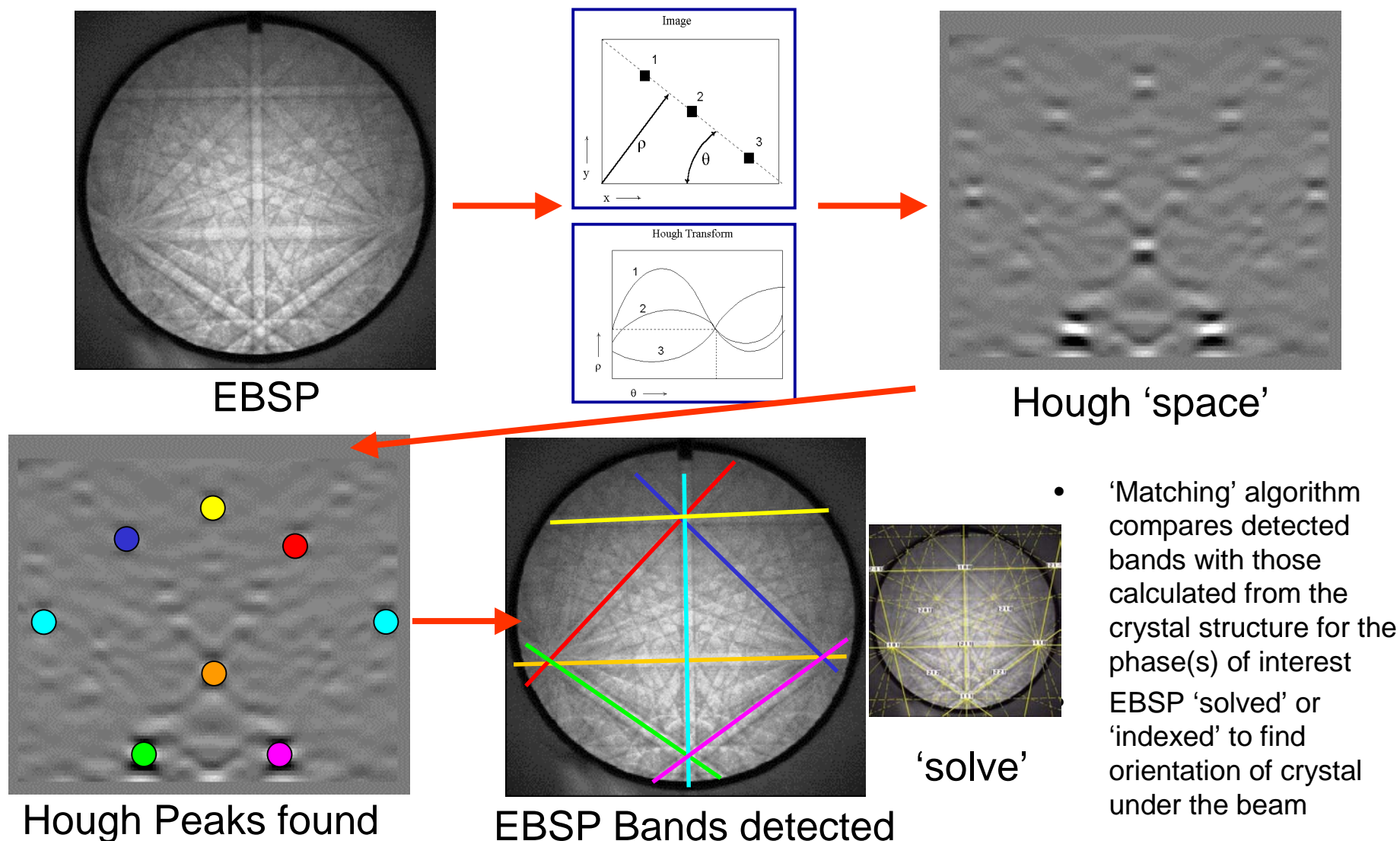


Silicon at 20kV

# Hi-res EBSP - Si 20kV



# From EBSD to Orientation

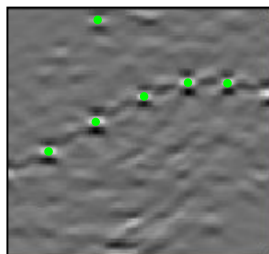




# Indexing: Phase discrimination & orientation determination (simplified)

## Band Detection

- List of angular relationships between detected bands
- Band positions on phosphor screen
- Other information also extracted (e.g. band widths)
- Highest intensity bands most likely to be detected



## Reflector Calculation

For each potential phase, list of allowed reflections, diffraction band widths and intensity hierarchy generated from kinematic electron diffraction theory or reflector list is loaded. Also, for reflections above an intensity cutoff, interband angles are calculated.

Match?

Yes

Phase discriminated  
Orientation determined

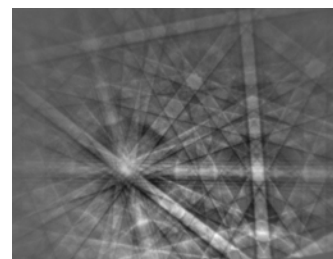
h k l	d [Å]	Intensity	visible (if not cropped)
1 -1 -1	3.1356	100.0	+
1 1 -1	3.1356	100.0	+
1 1 1	3.1356	100.0	+
1 -1 1	3.1356	100.0	+
2 -2 0	1.9201	65.5	+
2 0 -2	1.9201	65.5	+
0 2 -2	1.9201	65.5	+
2 2 0	1.9201	65.5	+
0 2 2	1.9201	65.5	+
2 0 2	1.9201	65.5	+
0 0 4	1.3578	24.7	+
4 0 0	1.3578	24.7	+
0 4 0	1.3578	24.7	+
1 -1 -3	1.6375	21.1	+
1 3 -1	1.6375	21.1	+
1 1 3	1.6375	21.1	+
1 -3 -1	1.6375	21.1	+
1 3 1	1.6375	21.1	+
1 -3 1	1.6375	21.1	+

# Indexing cycle

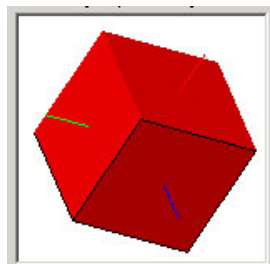
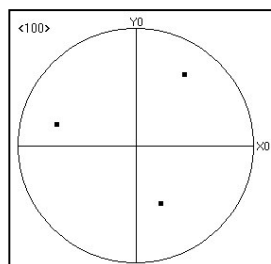
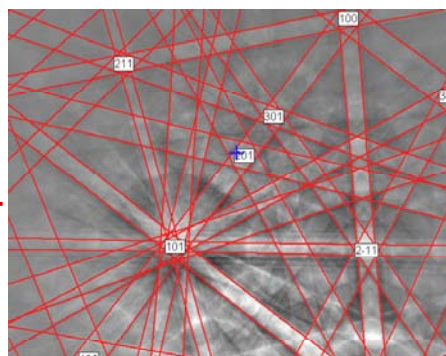
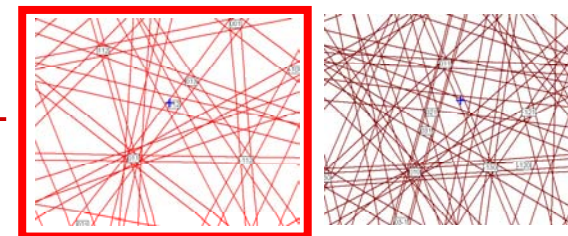
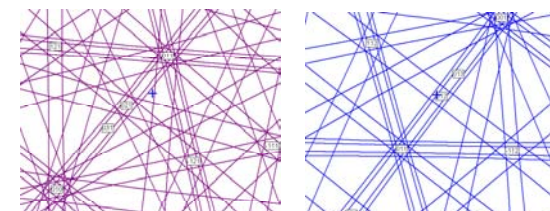
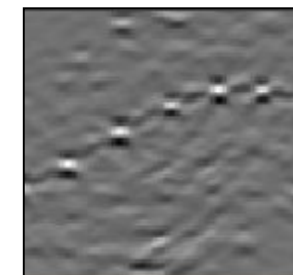
Position beam



Collect EBSD



Hough transform  
& band detection

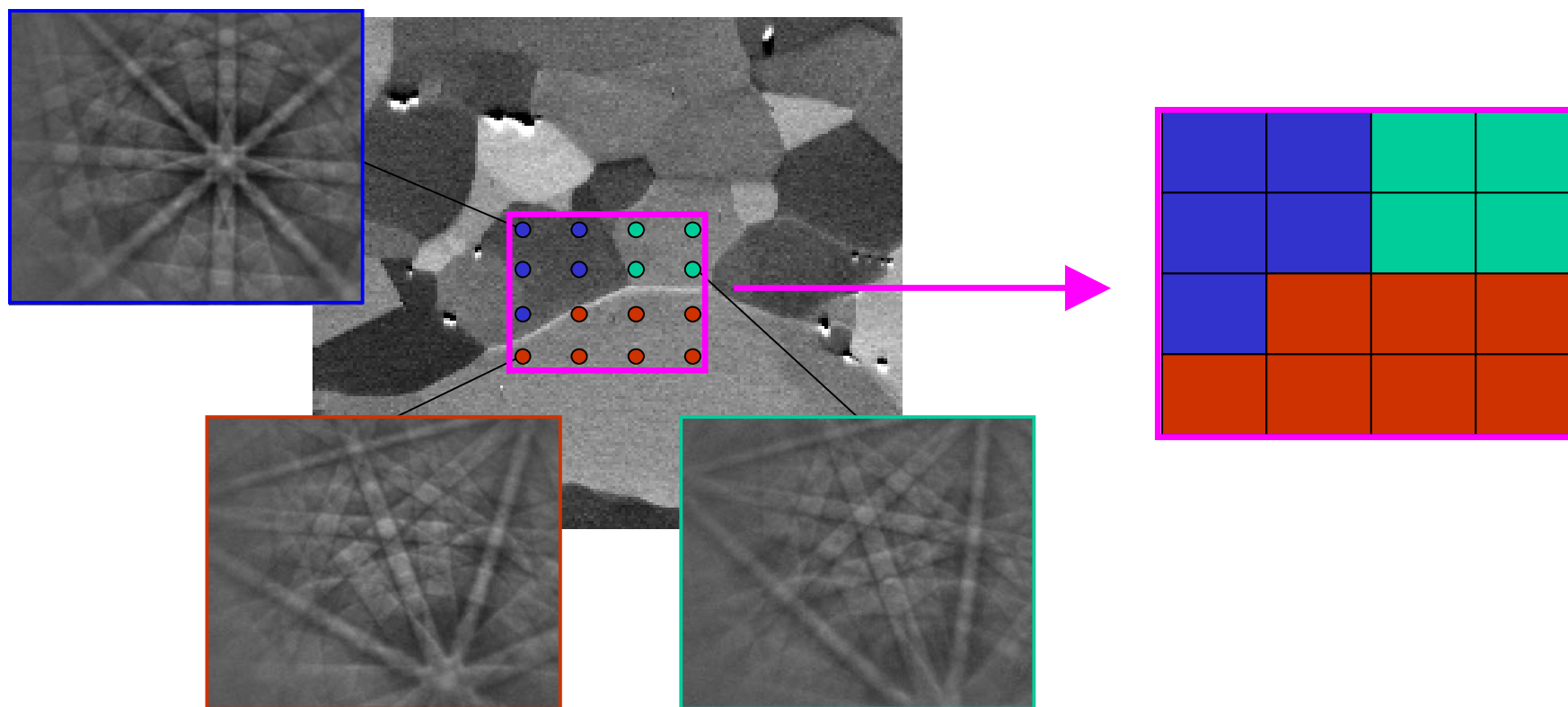


Phase and  
orientation

Verify match:  
Indexed EBSD

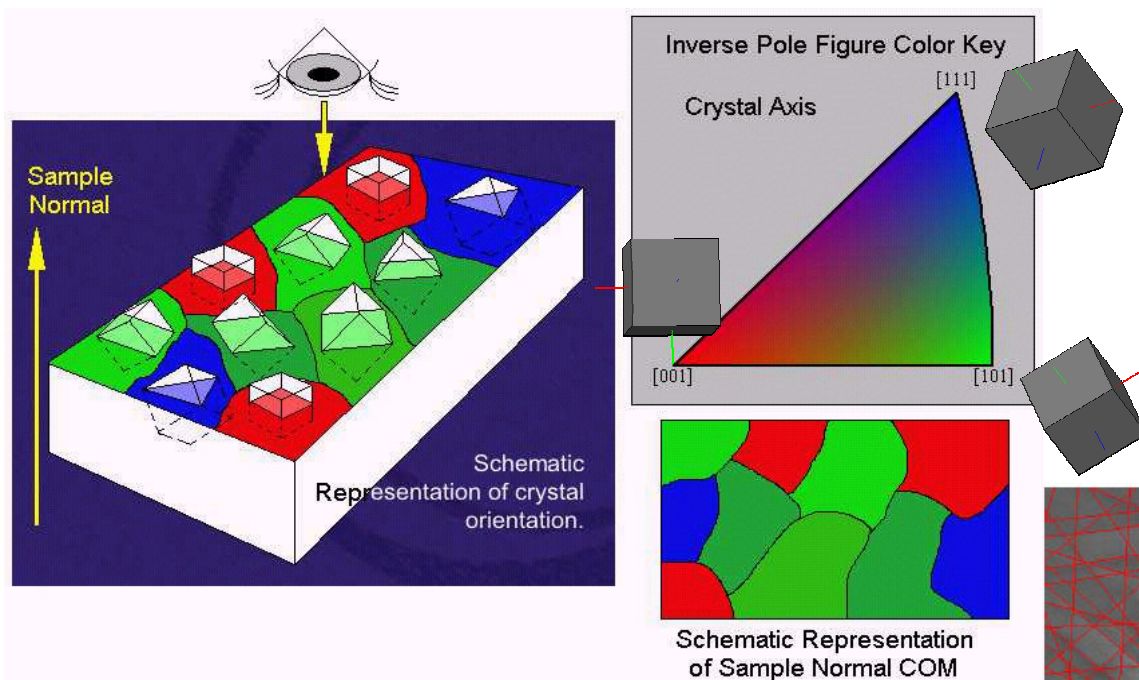
Match to phase & orientation

# Mapping



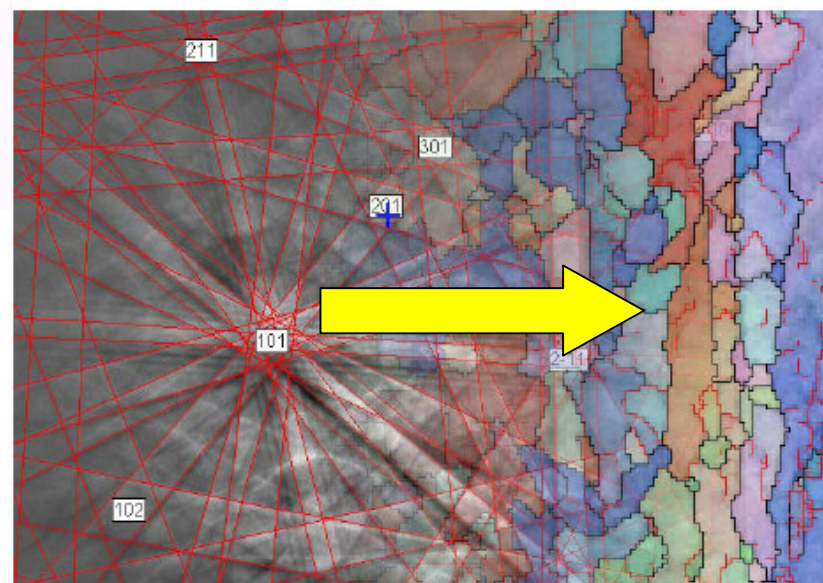


## From EBSP to Crystal Orientation Map



- COM with Inverse Pole key for cubic material
- Red = 100
- Green = 110
- Blue = 111 planes parallel to the surface

- Orientation obtained at every pixel
- Colour derived from inverse Pole Figure color key or Euler angles
- Hough transform for every pixel stored for post acquisition reprocessing



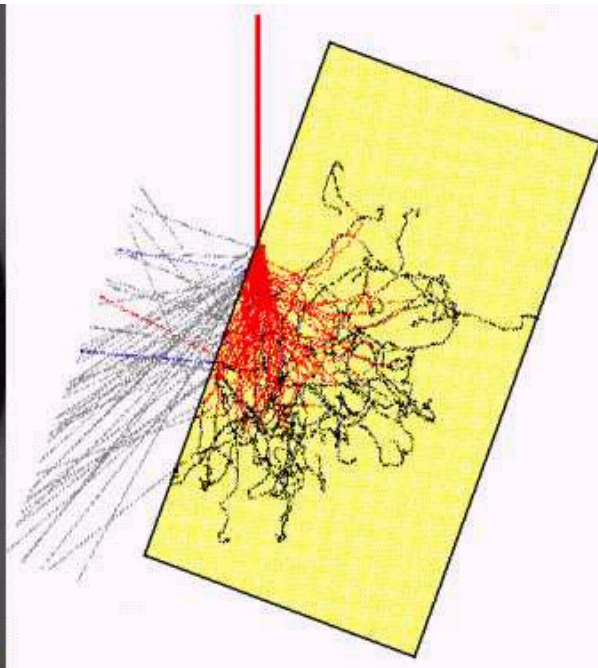
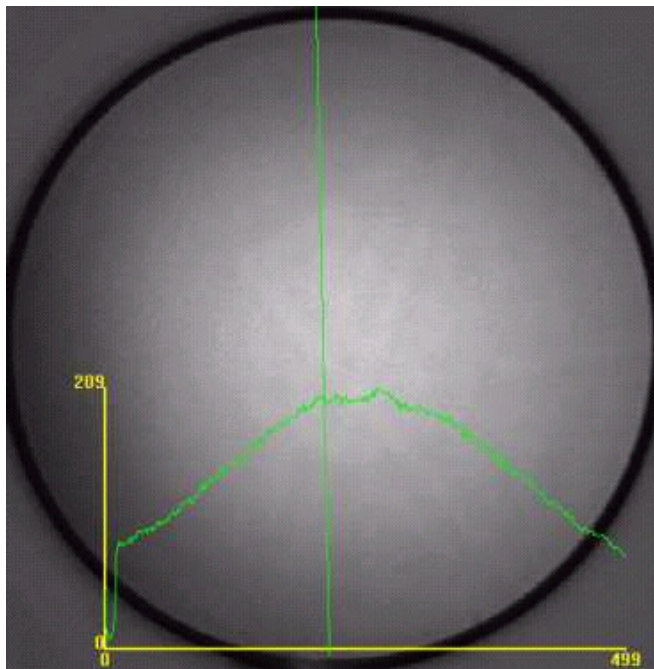
# Factors affecting EBSP Quality

Electron Back Scattered Patterns (EBSP's)  
vary greatly...



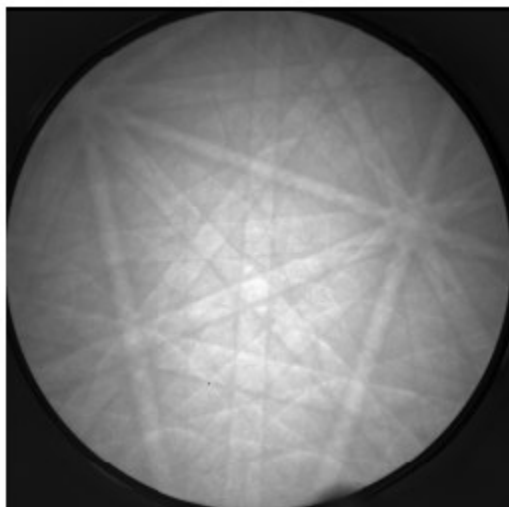
## EBSP 'Background'

- Only a small proportion of the electrons arriving at the phosphor screen are diffracted.
- Therefore the pattern is superimposed on a 'background'

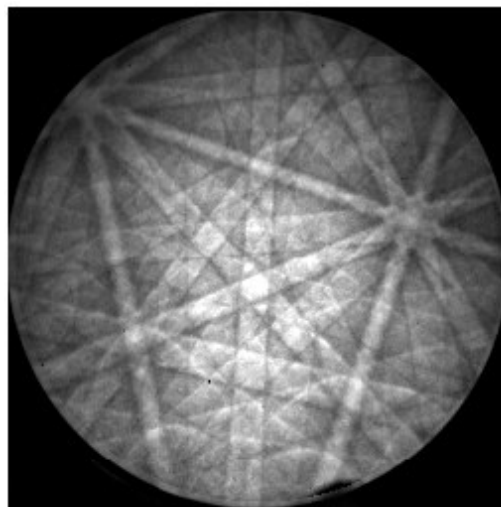


- Background removal is required to enhance pattern contrast

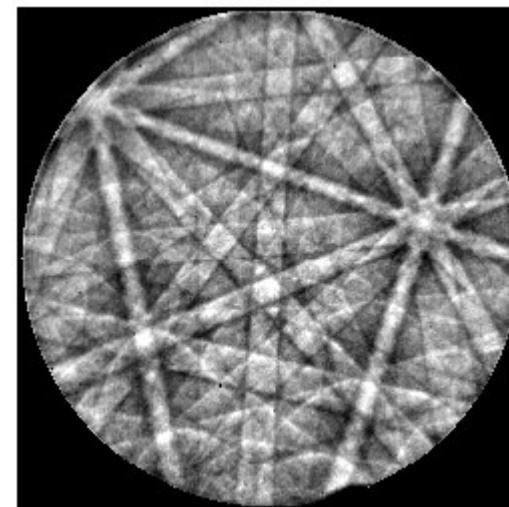
# Enhancing EBSP Contrast - Background Removal



Fe 20kV raw EBSP



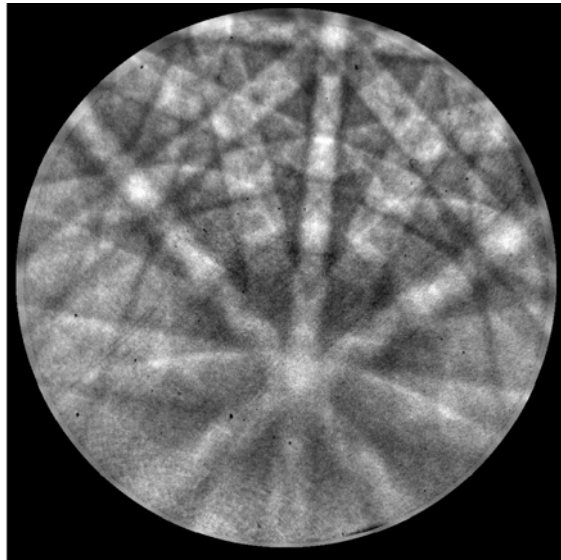
70% Background  
subtracted



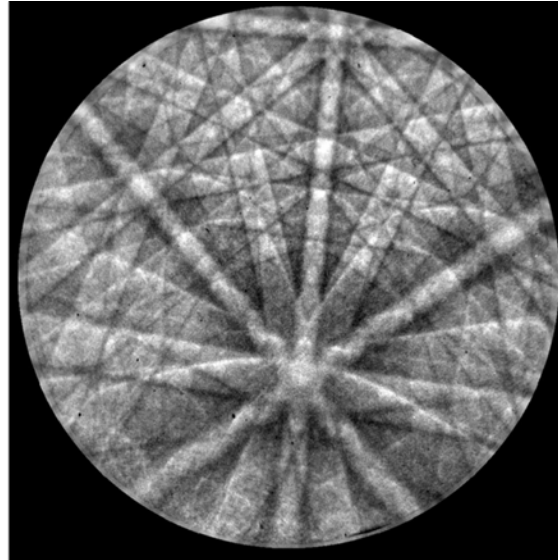
Background  
Divided

- EBSP contrast enhanced by background subtraction or division
- Particularly useful in lighter atomic number materials or when pattern quality (contrast) is low

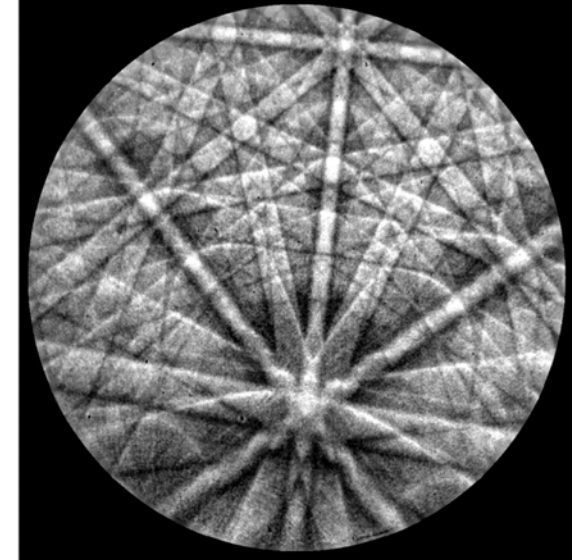
## Accelerating Voltage - Effect of kV on Pattern Quality



Nickel 10kV



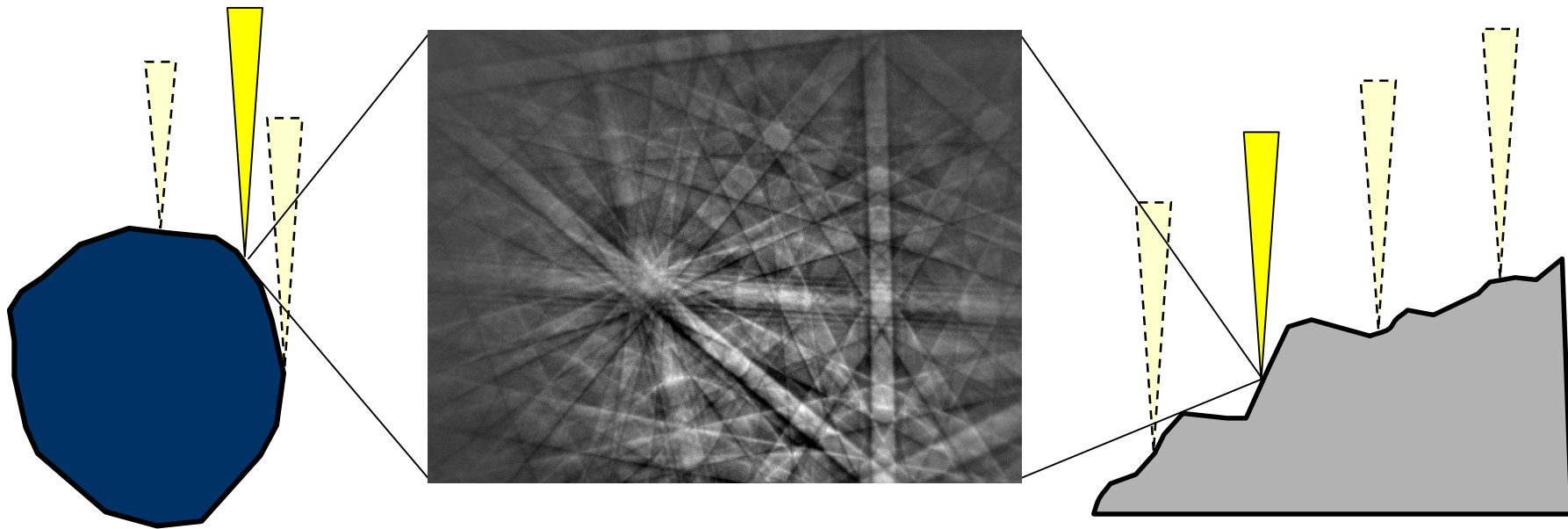
Nickel 20kV



Nickel 30kV

- Bands are broader and less sharp at low kV
- Band detection can be influenced by Hough parameters

## Sampling: Non-planar surfaces

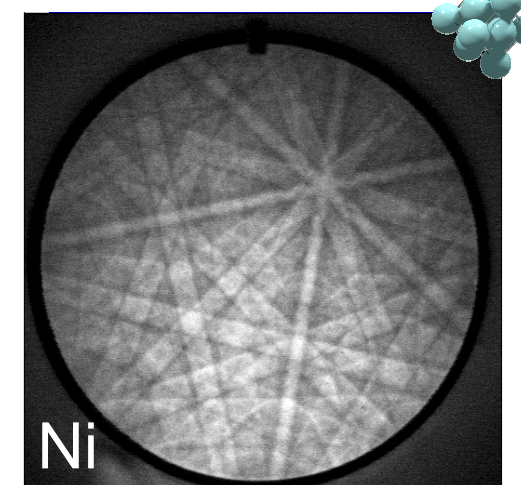
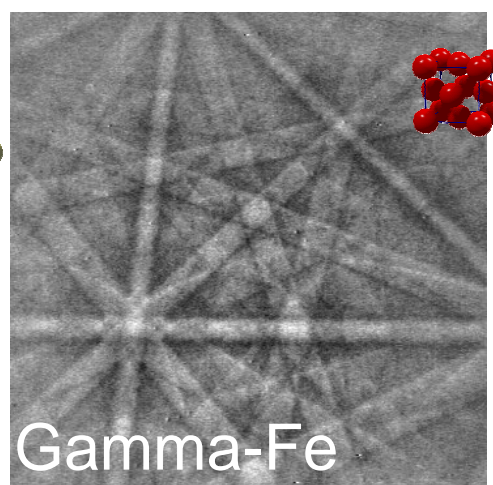
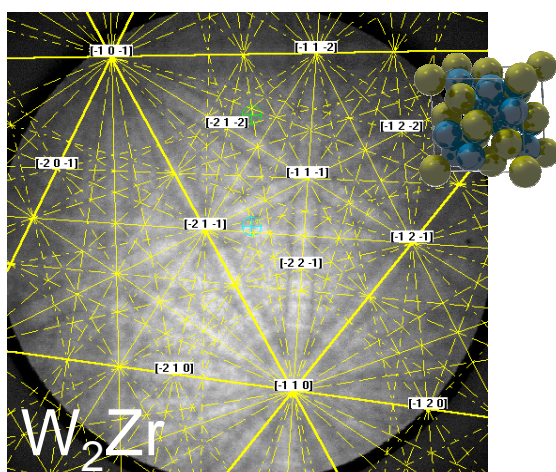
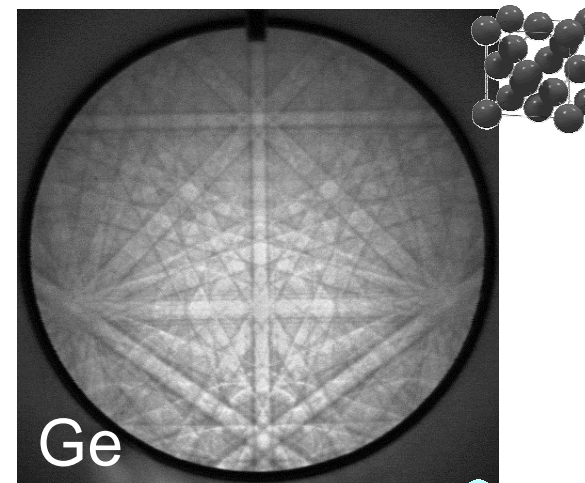
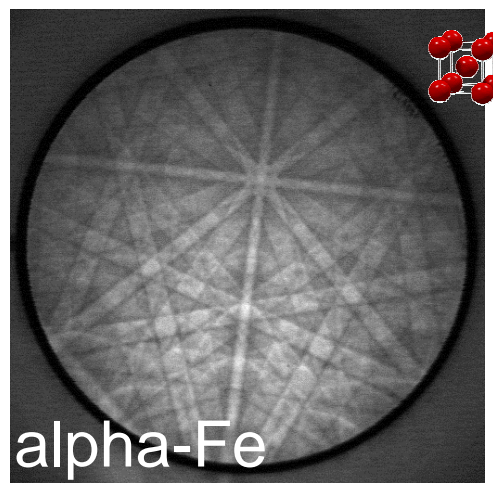
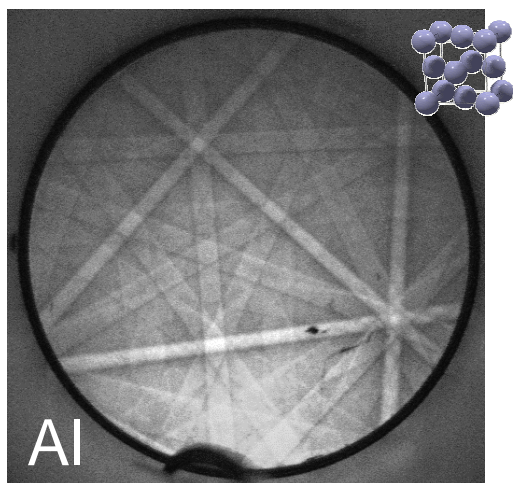


Sampling selection on fracture surface or free sediment

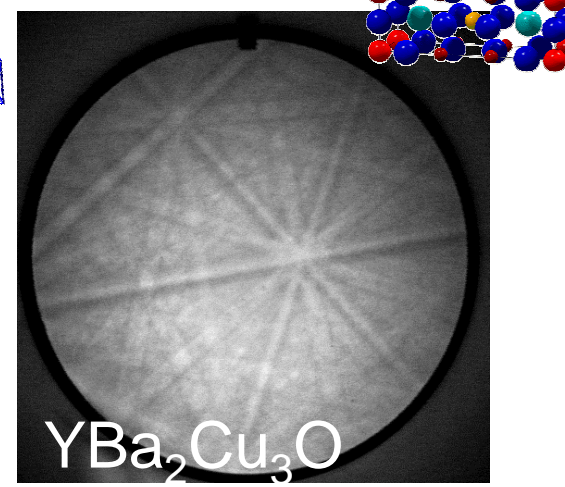
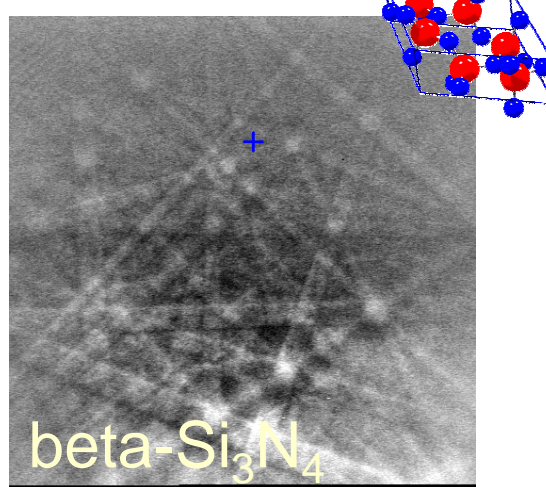
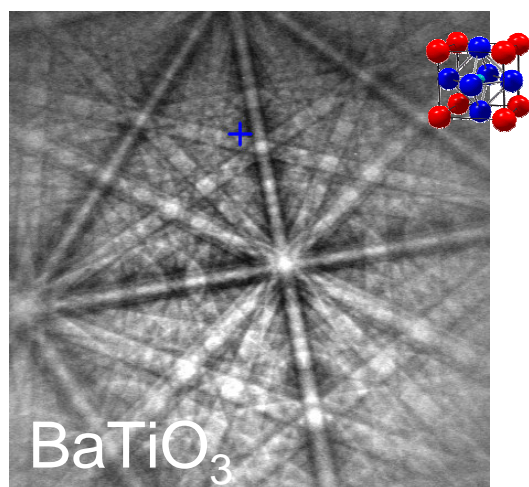
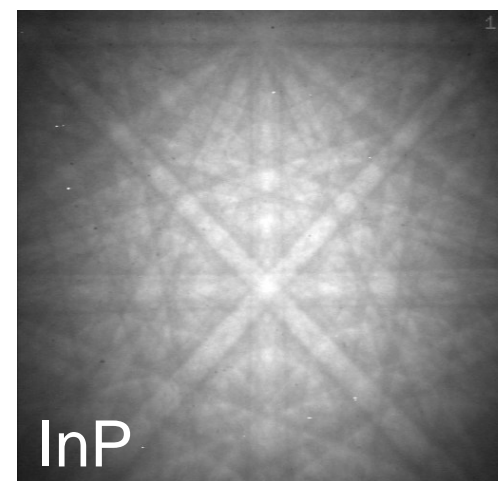
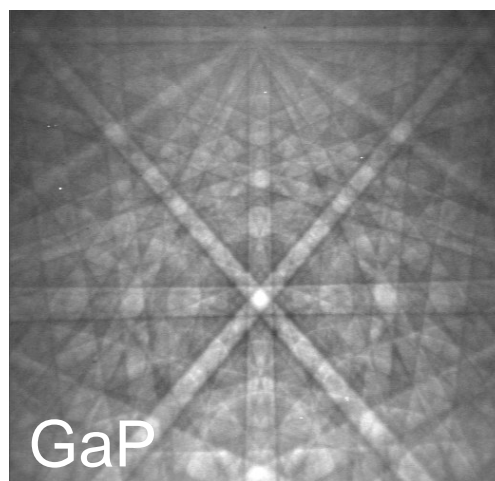
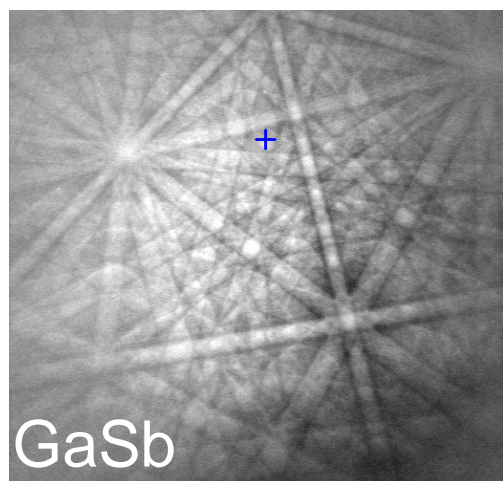
- Operator must search for locations where local topography & damage level allow clear patterns to reach detector
- FIB-SEM allows precision selection of areas for sectioning & mapping



# Examples of EBSDPs

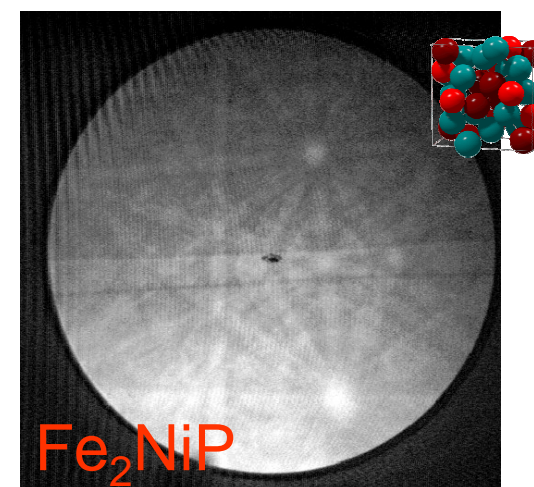
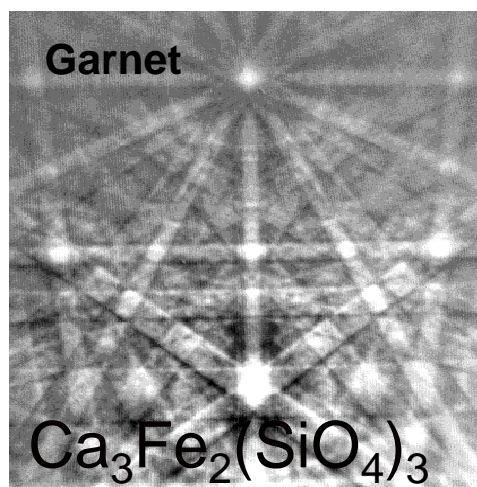
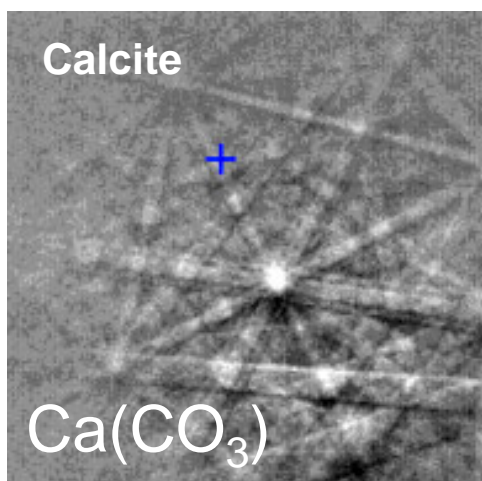
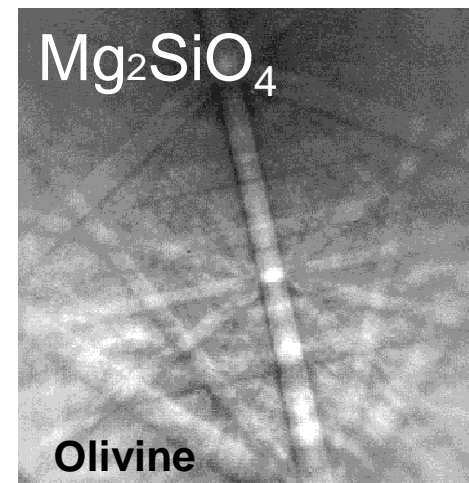
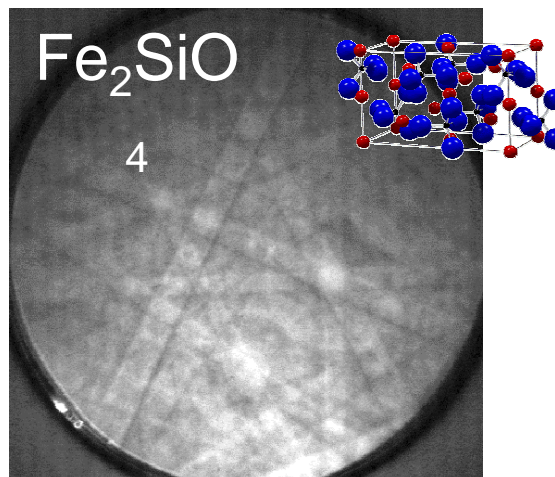
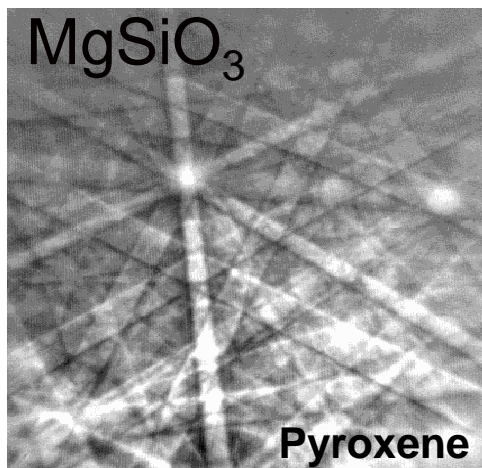


## Examples of EBSDPs



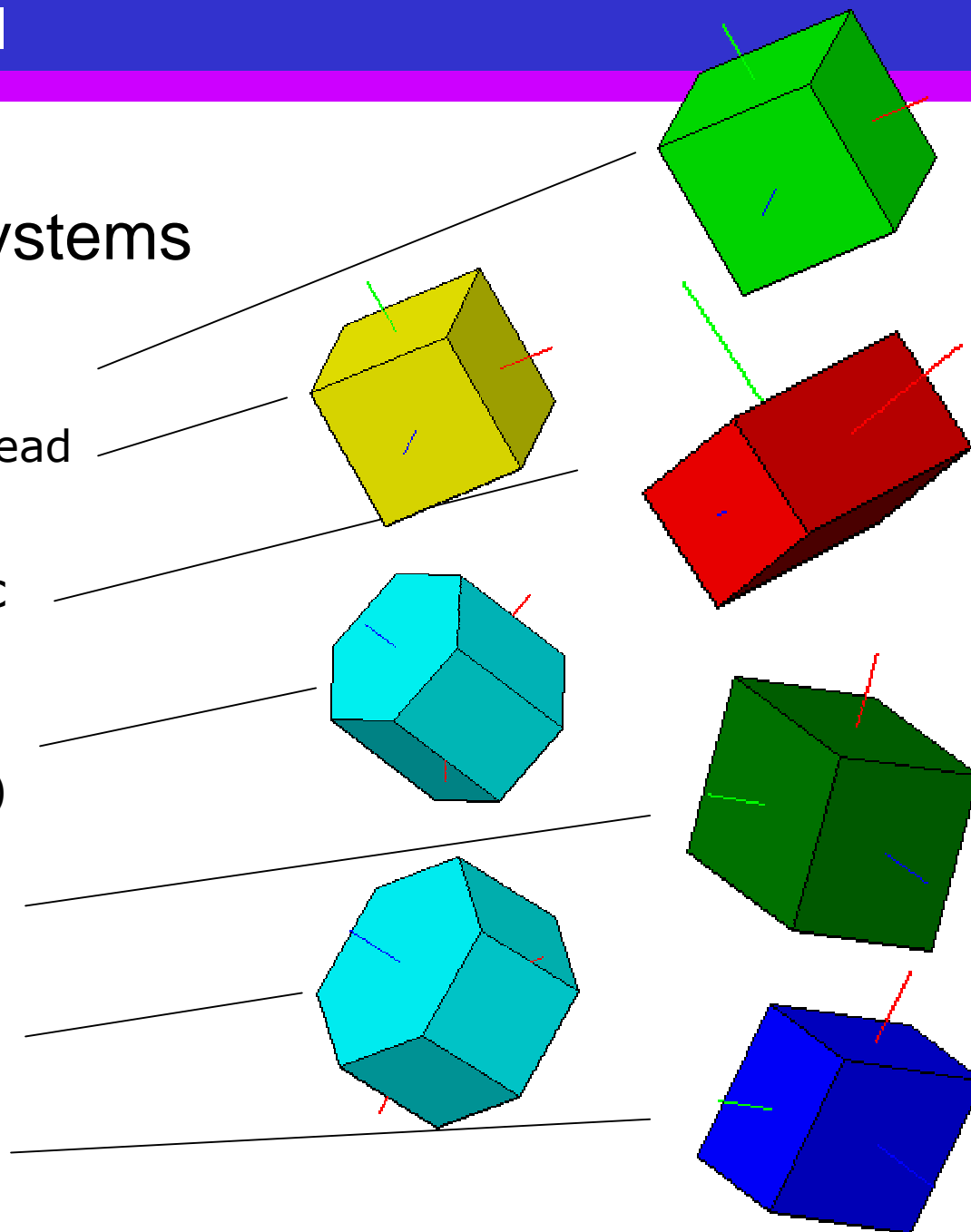


# Examples of EBSPs



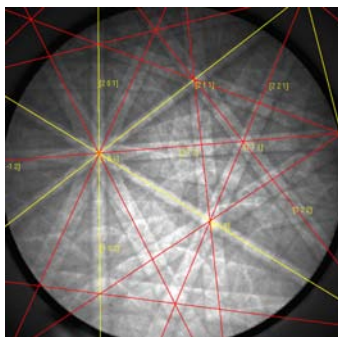
## Seven crystal systems

- Cubic (Al, Fe)
- Tetragonal (Lead Titanate)
- Orthorhombic (YBaCuO)
- Hexagonal (SiC, Titanium)
- Monoclinic (Zirconia)
- Trigonal (Quartz)
- Triclinic (Kyanite)

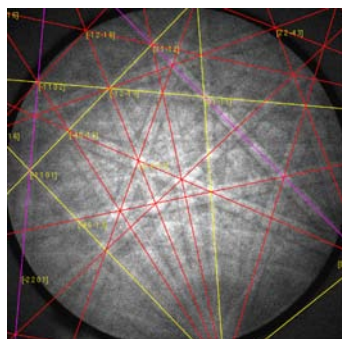




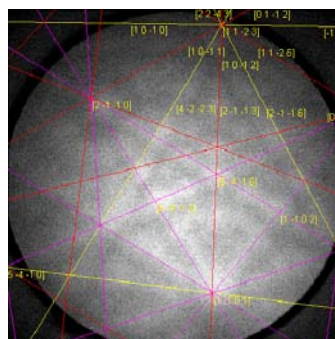
# 7 Crystal Symmetry Systems



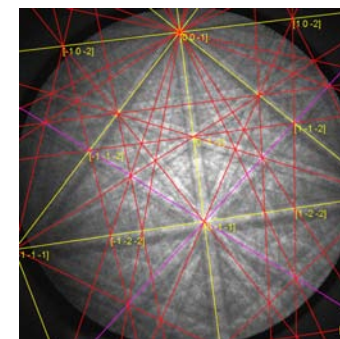
Cubic



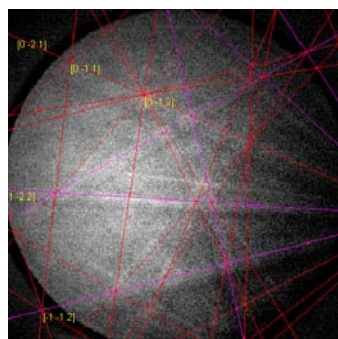
Hexagonal



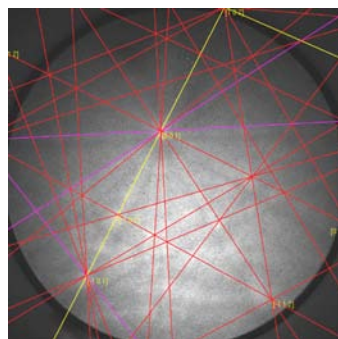
Trigonal



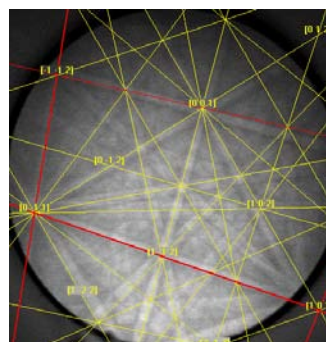
Tetragonal



Orthorhombic



Triclinic



Monoclinic

- Examples of all seven crystal systems solved

# Summary of Factors Affecting Pattern Quality

Acquisition conditions affect the EBSP:

- Band width varies with kV
- Band contrast varies with kV
- Band sharpness varies with kV
- Camera Sensitivity ('binning' level/resolution)
- Background removal
- Integration time
- Beam current (spot size) & current density
- Vacuum level
- Microscope resolution/aberrations

Sample conditions affect the EBSP:

- Atomic number
- Grain size
- Preparation damage/residues
  - surface contamination e.g. carbon from SEM
- Surface oxidation or reaction products
- Surface morphology
- Surface coatings
- Amorphised surface - ion milling

The Hough Transform can be configured to optimize band detection for a wide range of operating and sample conditions...

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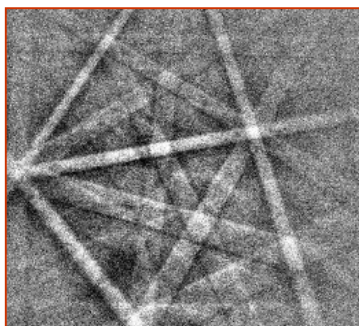
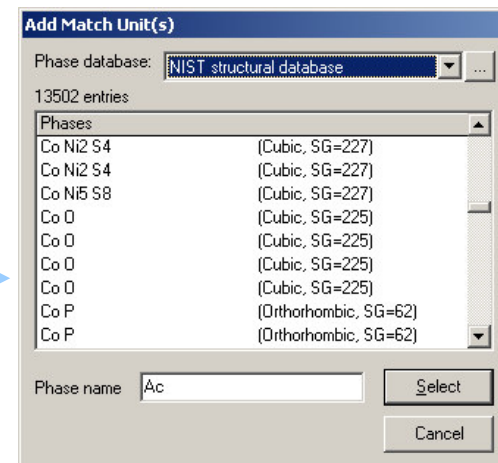
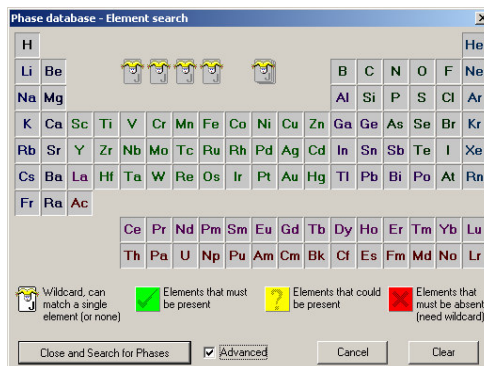
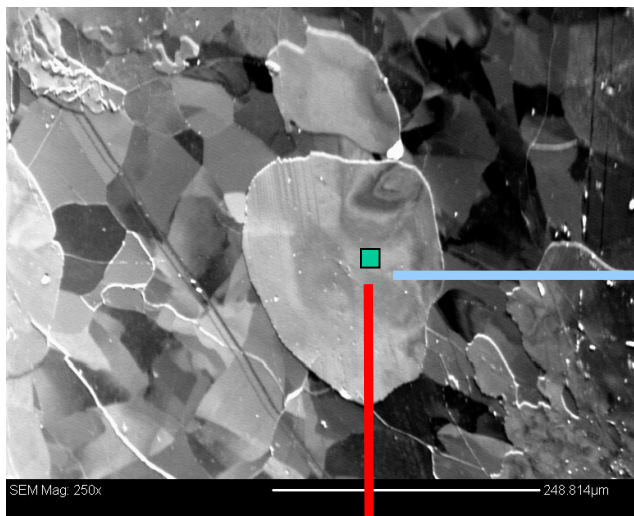
# Basic Modes of Operation

1. Point Analysis
2. Mapping

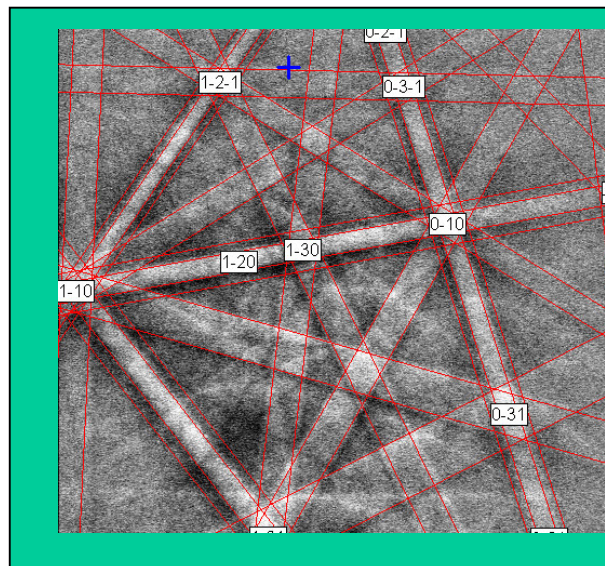
# Phase Discrimination

Acquire Chemistry

Search Structural Database



Acquire EBSP



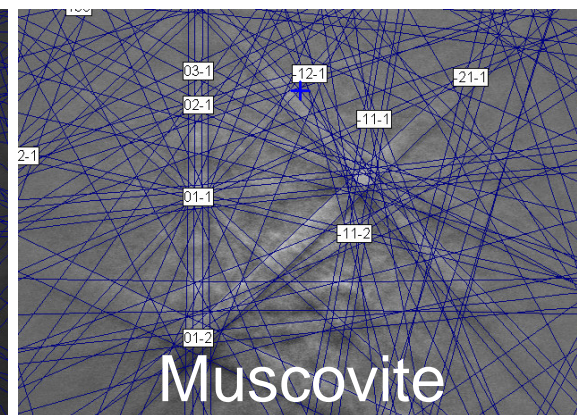
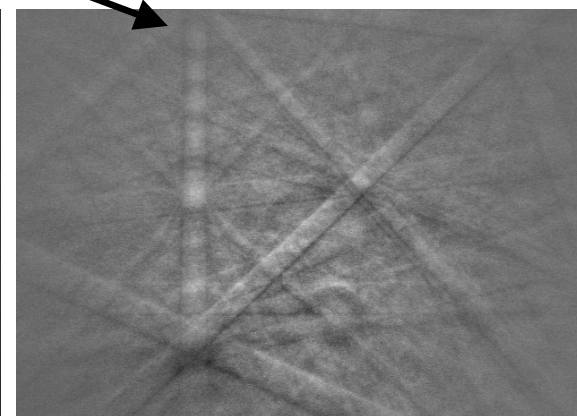
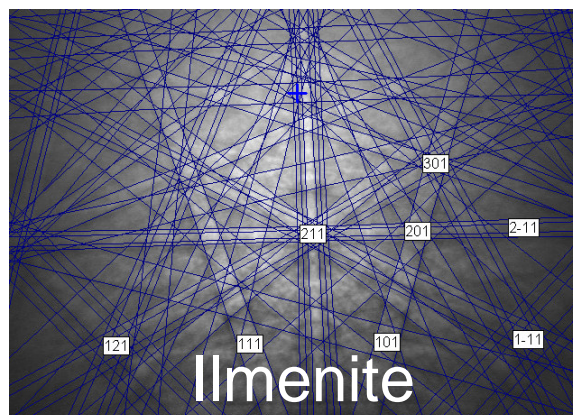
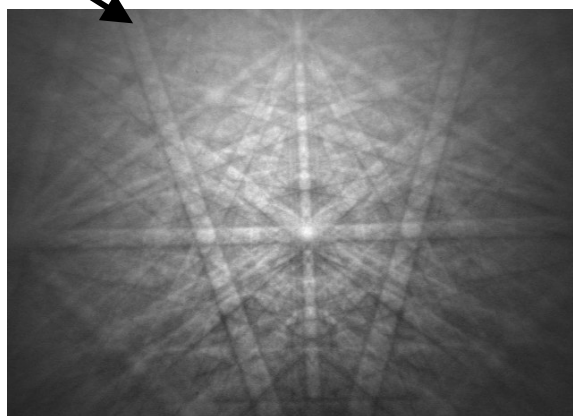
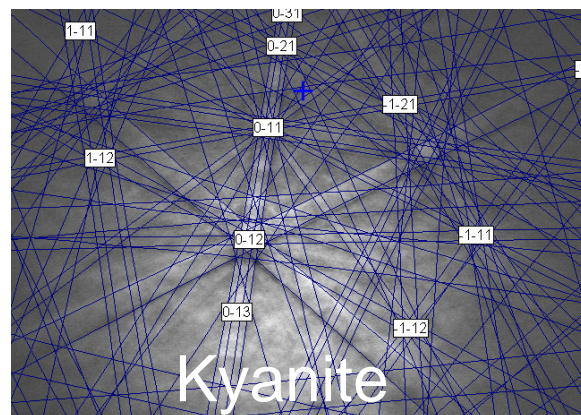
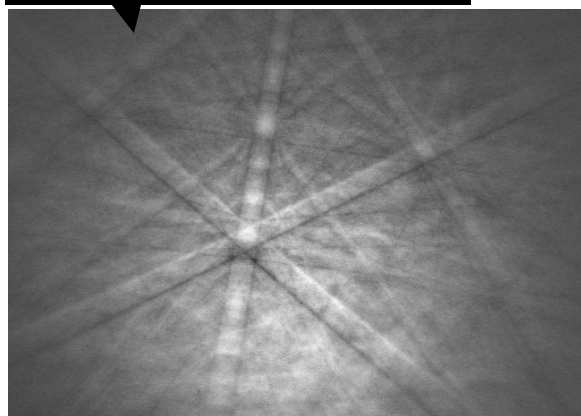
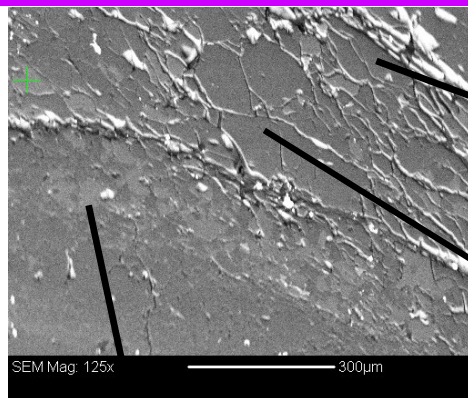
Index...

Solutions:		
Phase	MAD	Bands
Aluminium	0.0521	6
Al As2 Cs3	1.9693	6
Al As2 Cs3	1.9697	6
Al As2 Cs3	1.9829	6

Phase  
Identified



# Phase Discrimination by EBSD



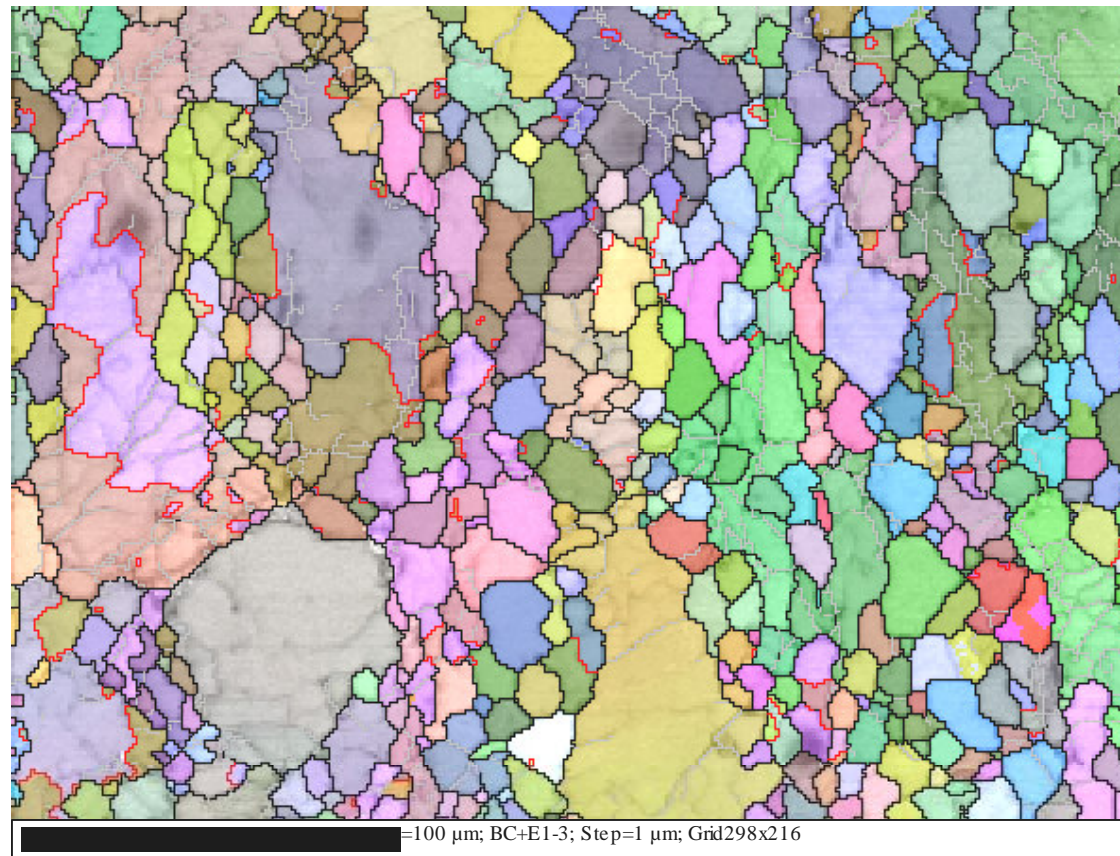
# Mapping

## General Examples



# Visualisation of data - general microstructure

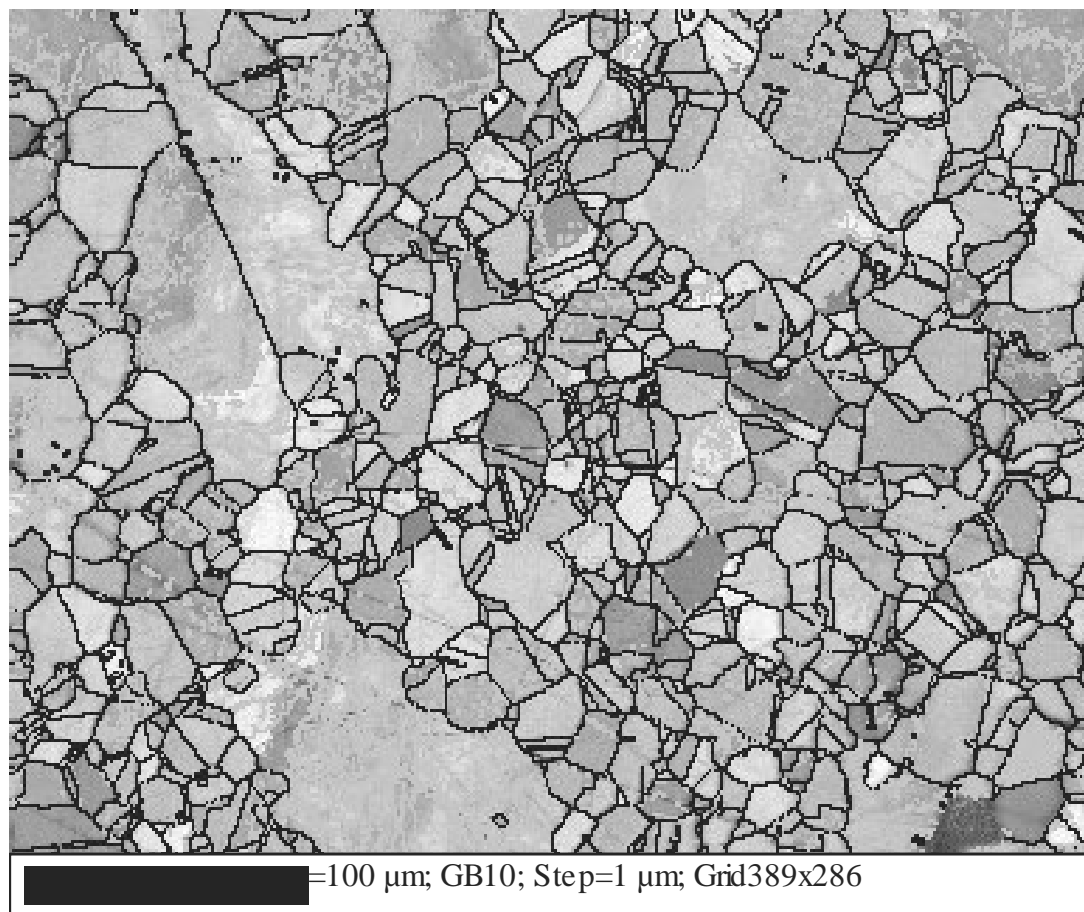
Quartzite



Orientation map + pattern quality + grain boundaries

# Map Display Options

Ni Superalloy



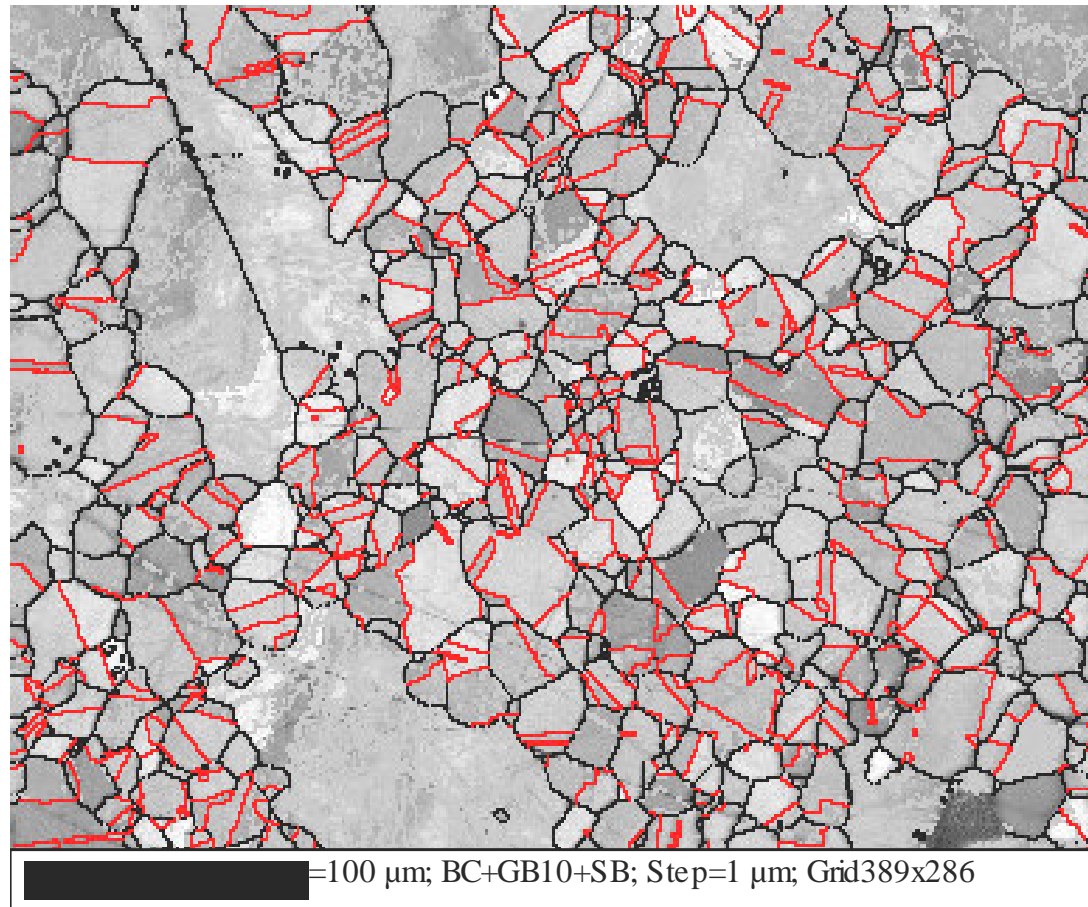
Band Contrast + Grain Boundaries (high angle – general)

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# Map Display Options

Ni Superalloy

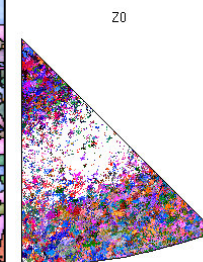
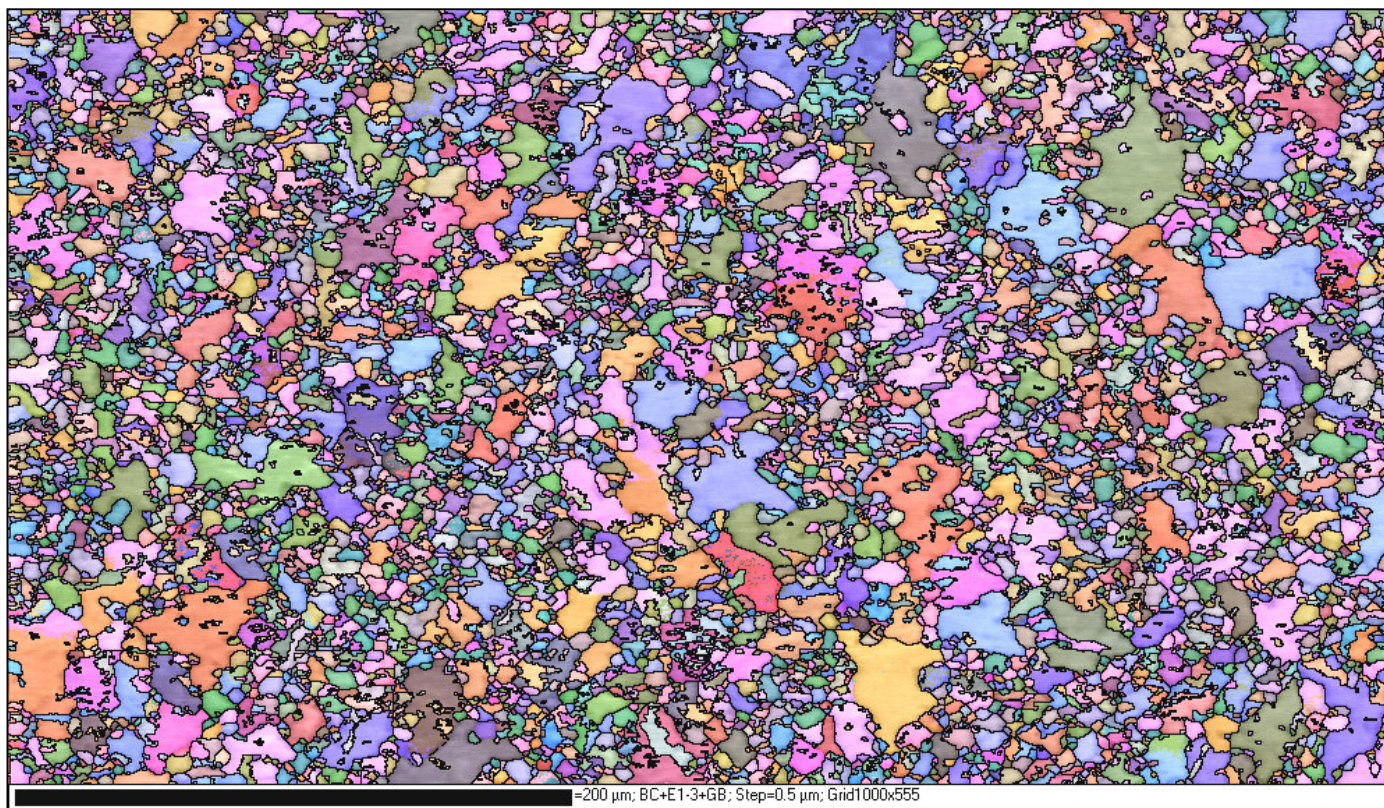


Band Contrast + Grain Boundaries + Twins/CSLs

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# Map Display Options

Cu thin film



All Euler orientation + pattern quality map



# Map Display Options

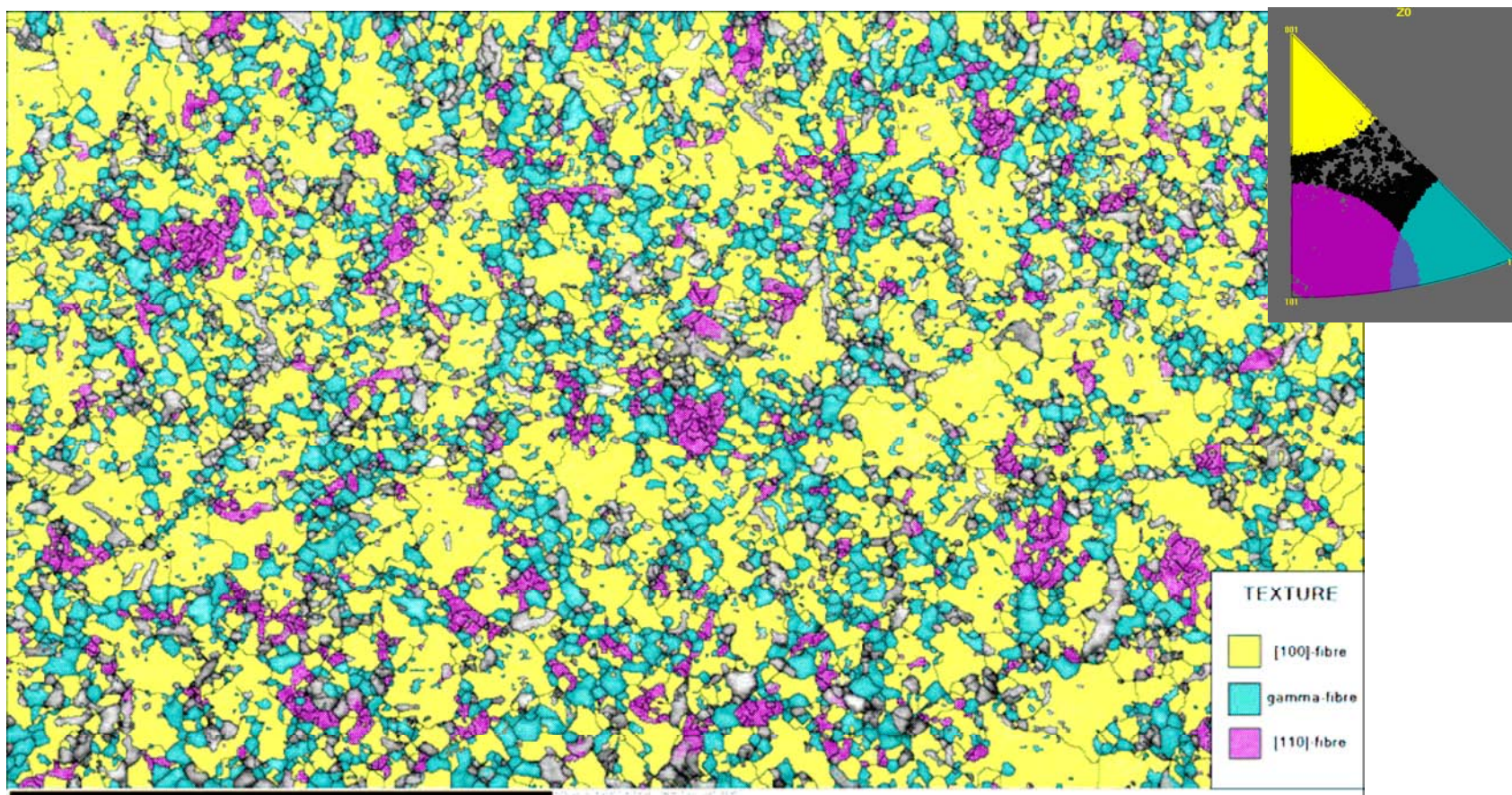
Cu thin film



Band contrast + GB map



# Map Display Options

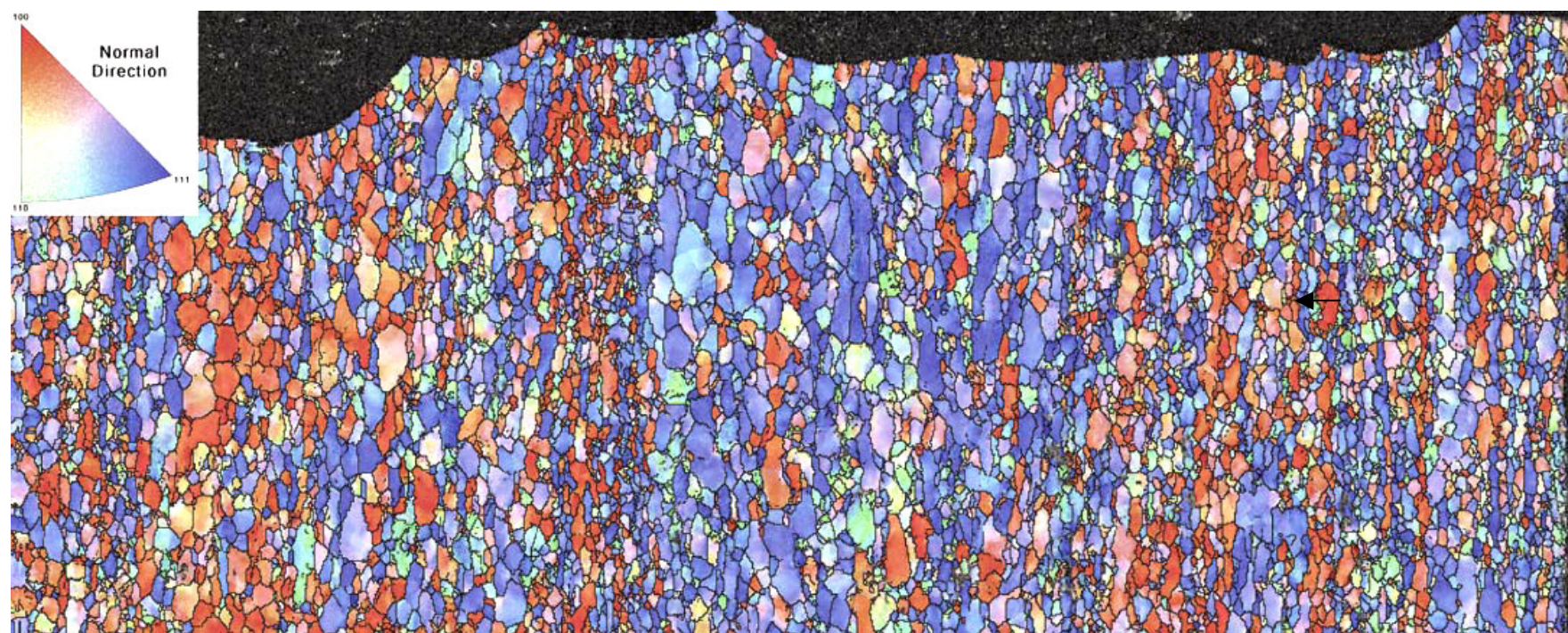


Grouped orientation map



# Map Display Options

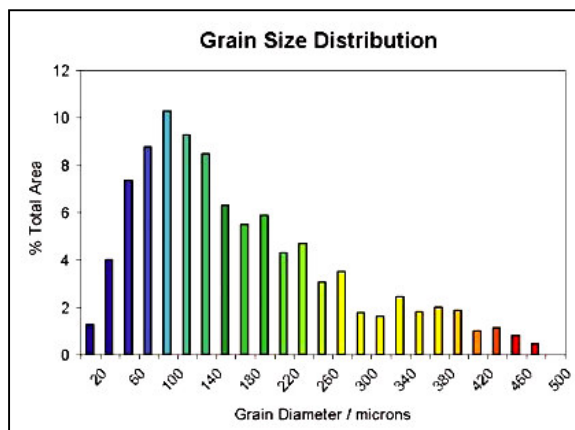
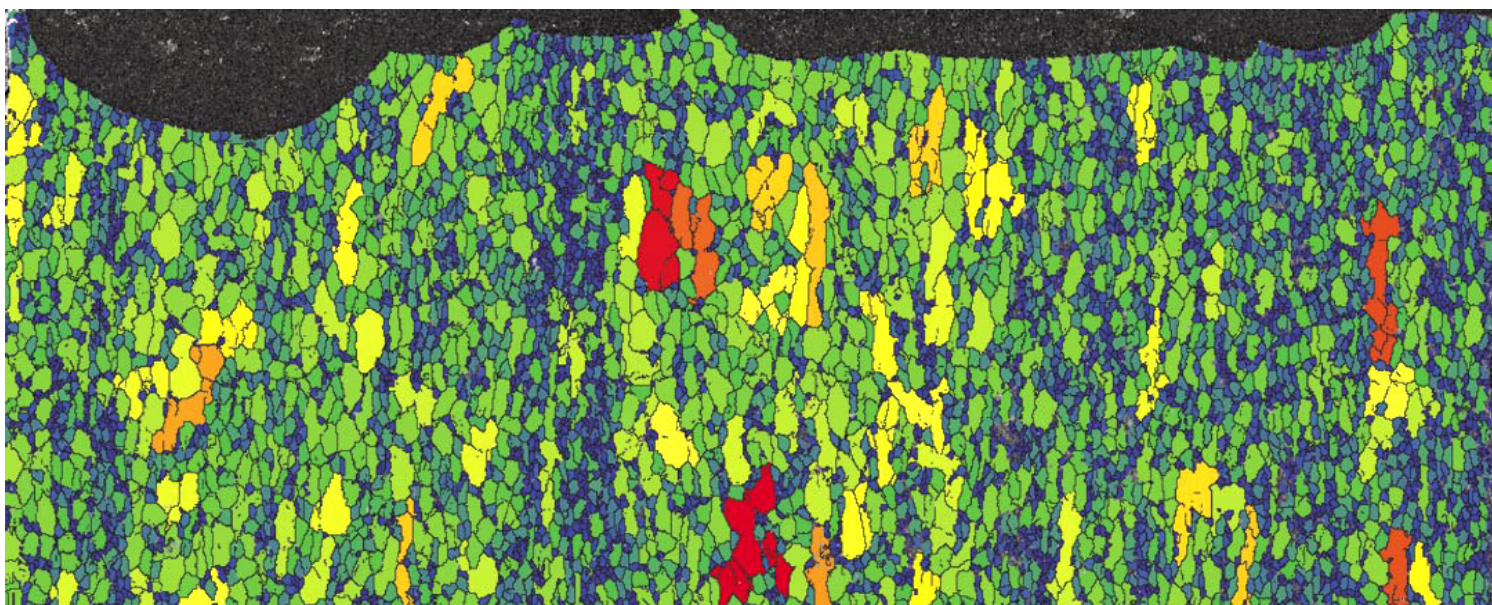
Ta sputter target



IPF-based orientation + pattern quality map



# Map Display Options

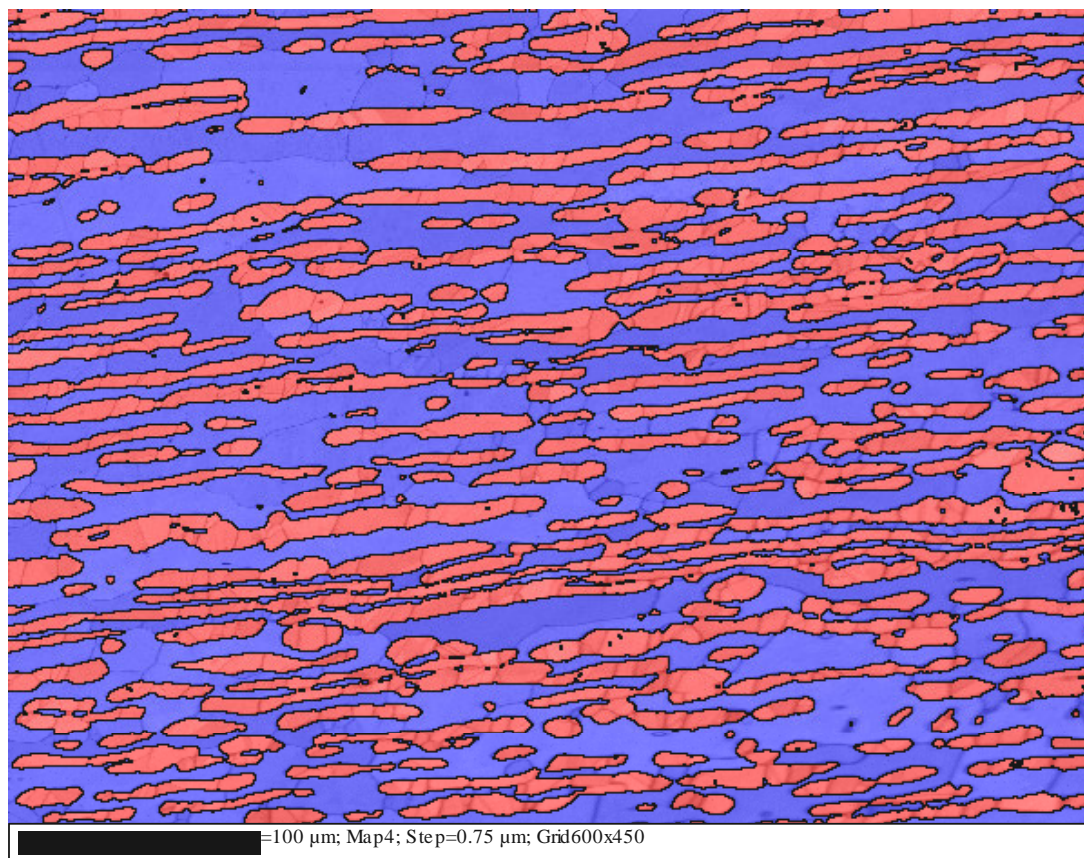




Map with grain size  
coloring scheme

Grain size  
distribution

# Phase Area Fraction & Distribution

Duplex Steel



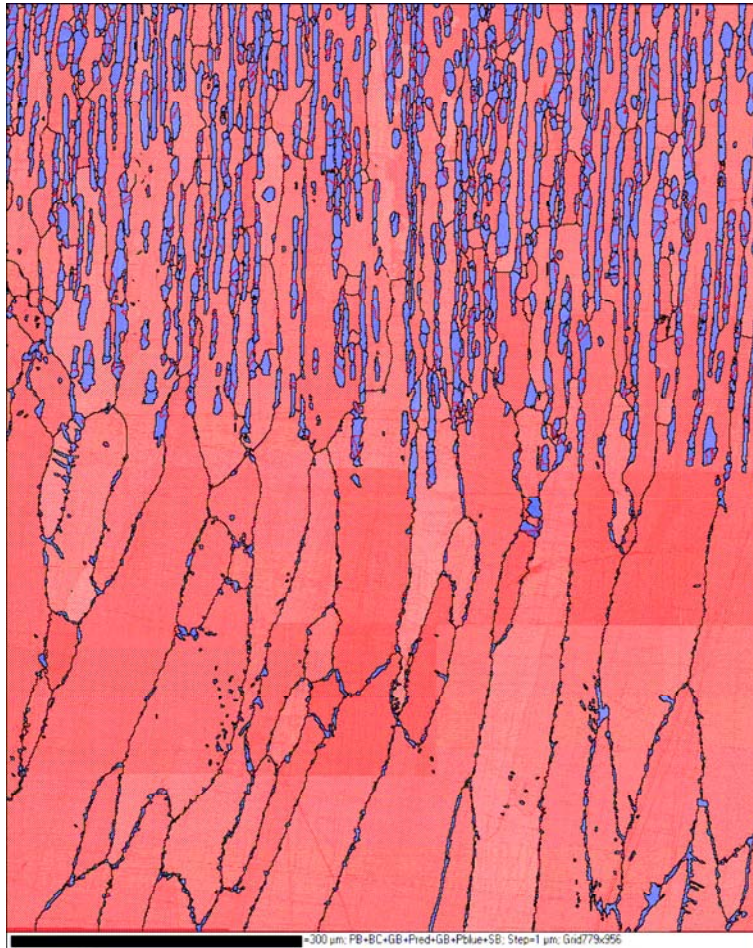
Phase-BLUE	Iron bcc [57.5%]
	
Phase-RED	Fe-FCC [42.5%]
	

Statistics				
Phase	%	mean BC	mean BS	mean MAD
Zero solutions	0	n/a	n/a	n/a
Fe-FCC	42.48	167.6	86.33	0.5486
Iron bcc	57.52	162.3	90.17	0.5348
Total	100	164.6	88.54	0.5407

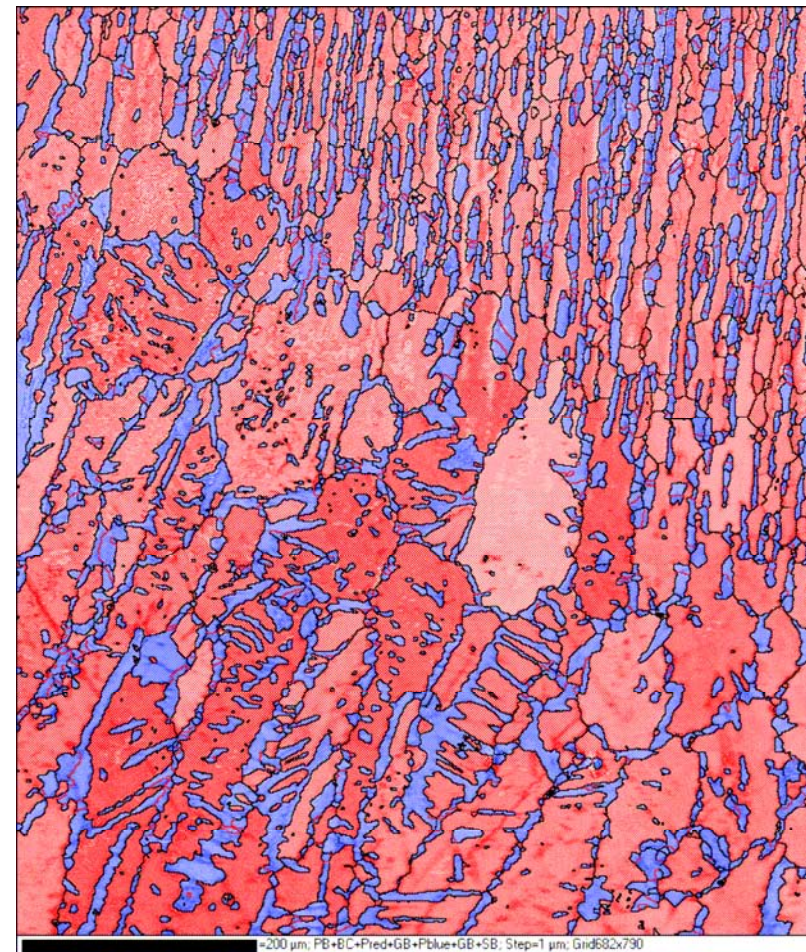


# Applications Example: Phase distribution & texture in laser welded duplex steel

Non-preheated



Preheated

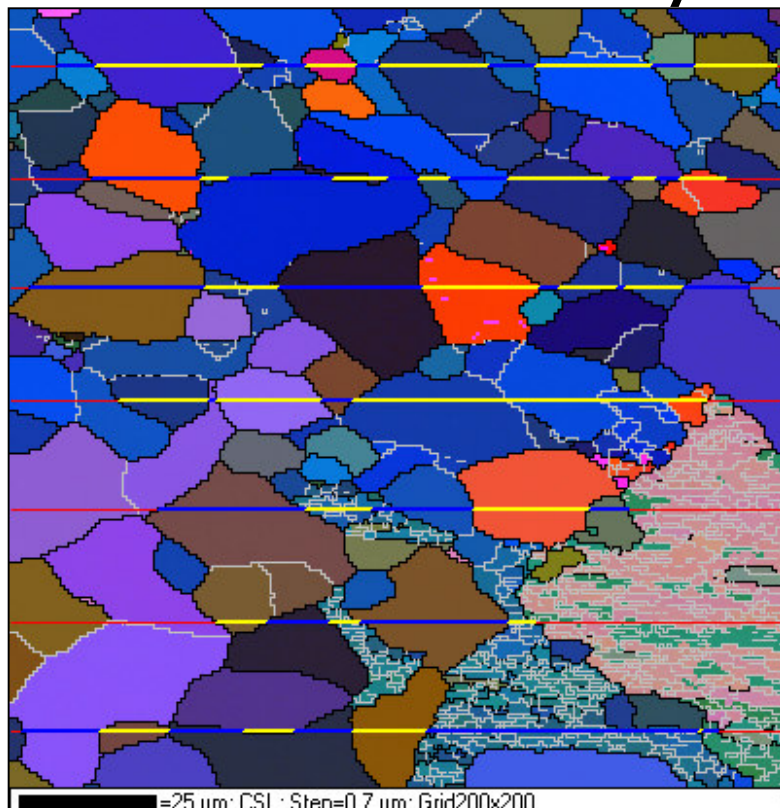


Phase maps (+ GBs): red = ferrite, blue = austenite

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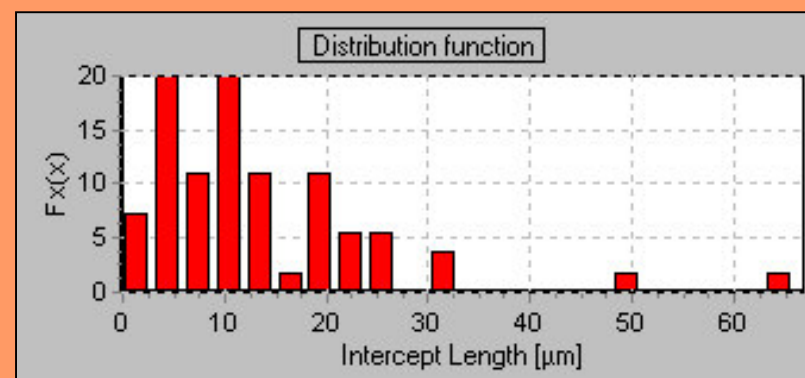
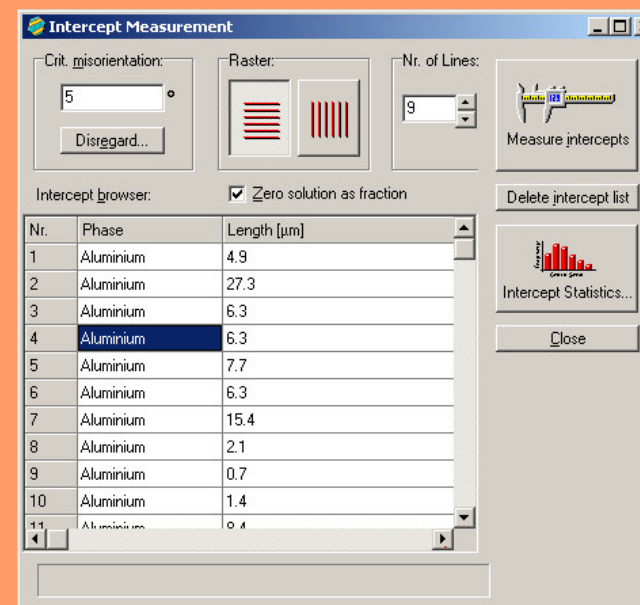


# Grain Size Analysis:



Unlike optical line-intercept GS analysis, twin boundaries and low-angle grain boundaries are positively identified and filtered from the data (if desired); tricky GB etch techniques not necessary; weaknesses of relying on reflected light orientation contrast are avoided

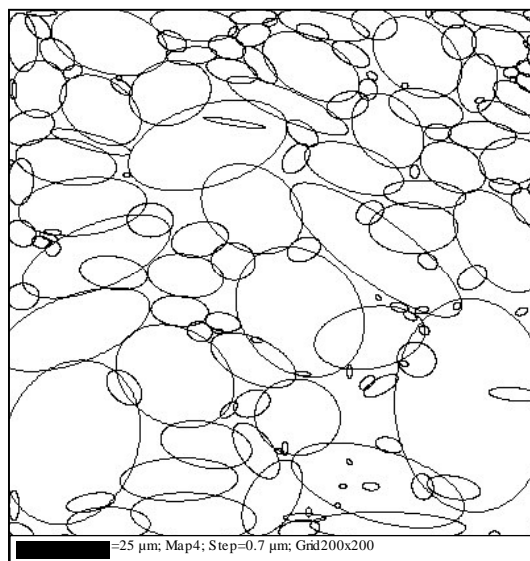
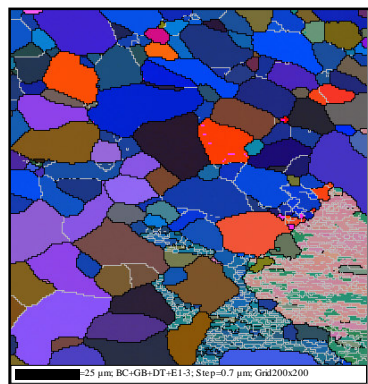
## Line Intercept Method



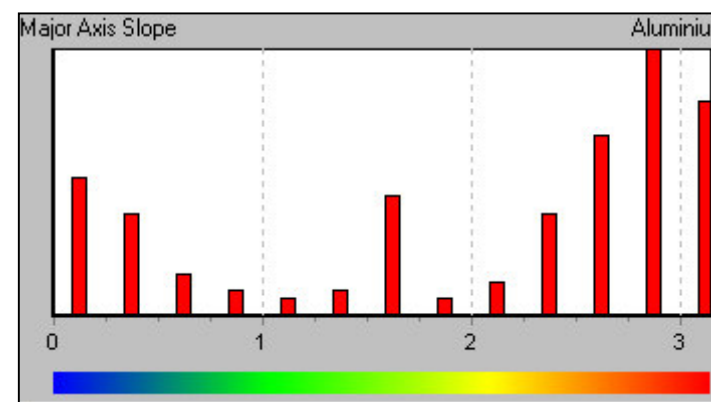
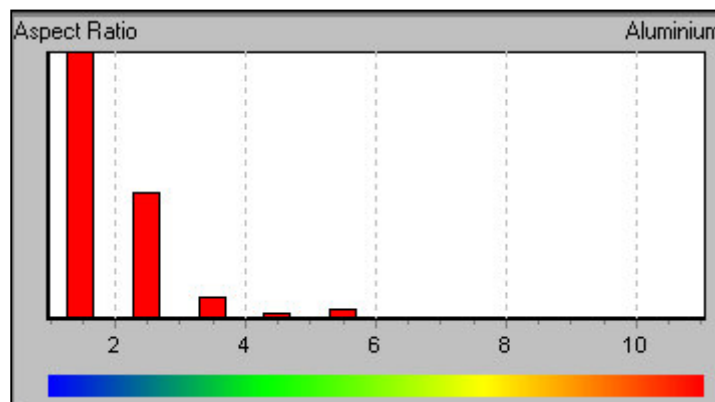
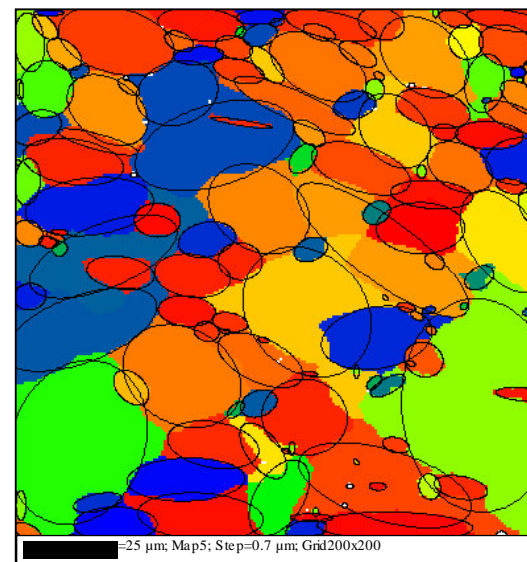
Data available as text and in graphical format

# Grain Shape Analysis

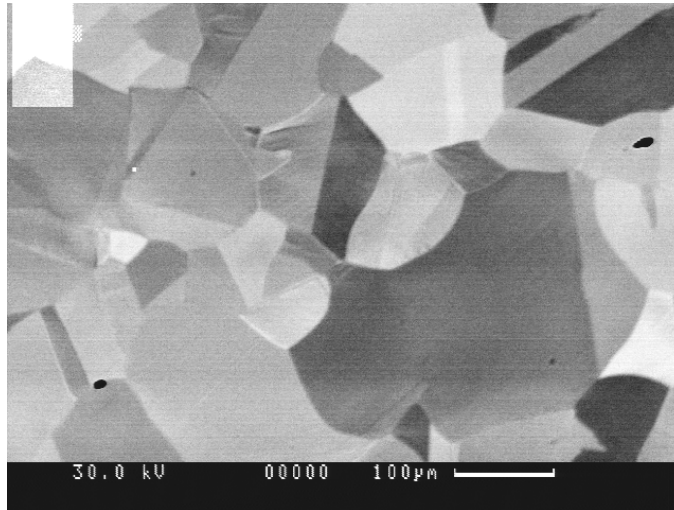
Aspect Ratios



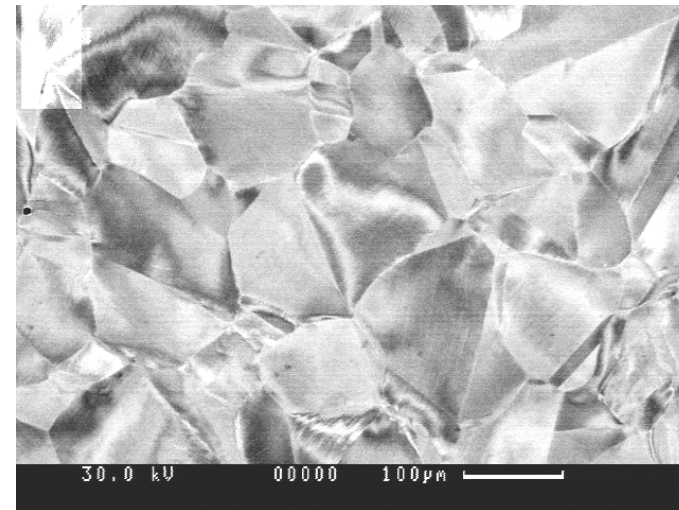
Major Axis Orientation



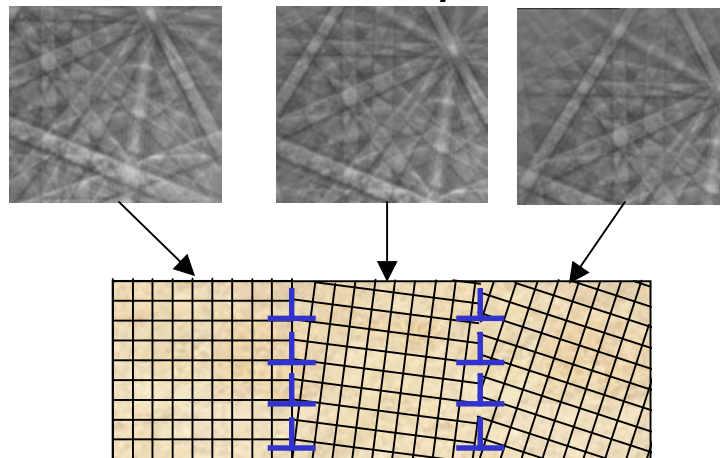
# Analysis of strain



Recrystallized



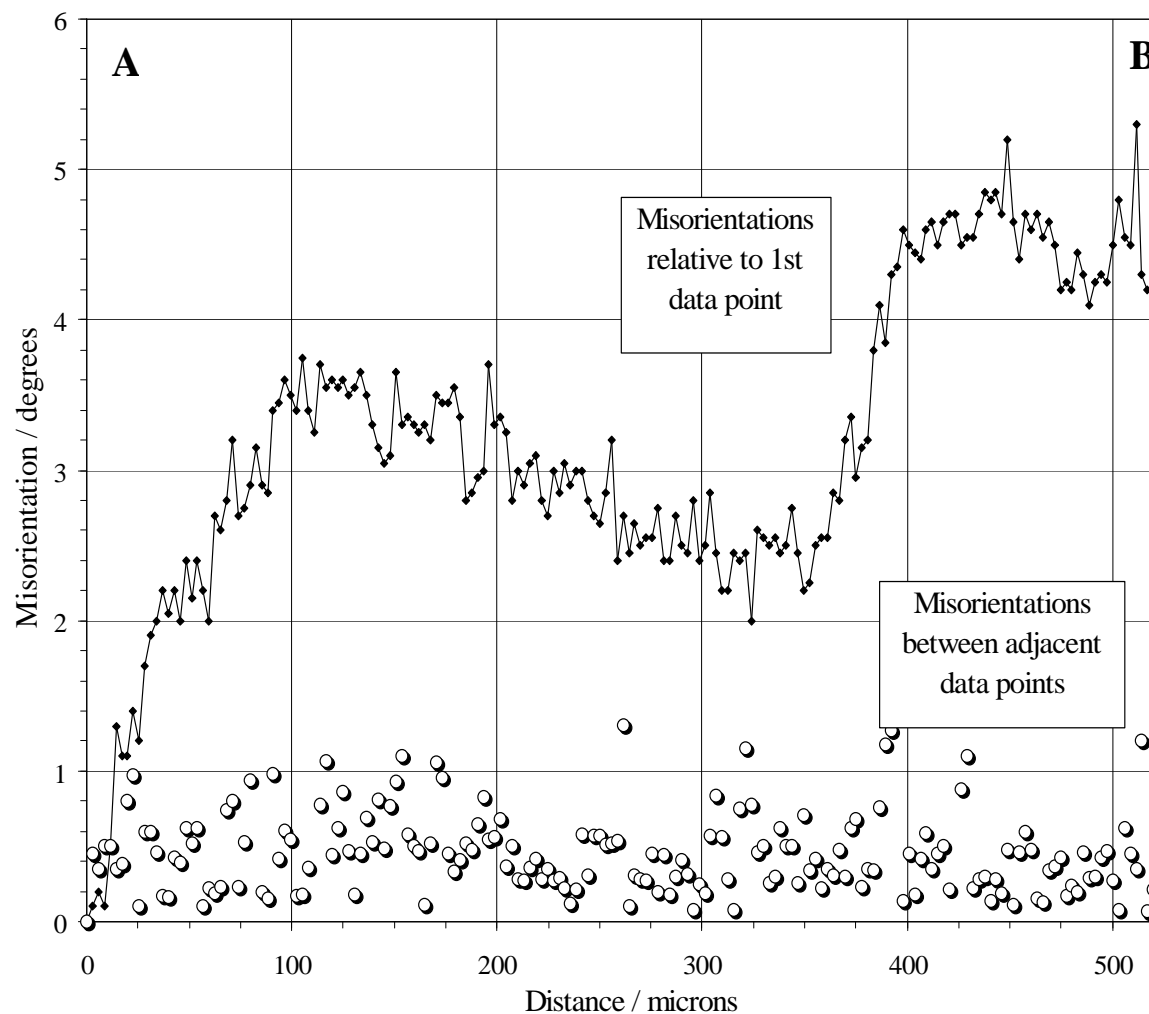
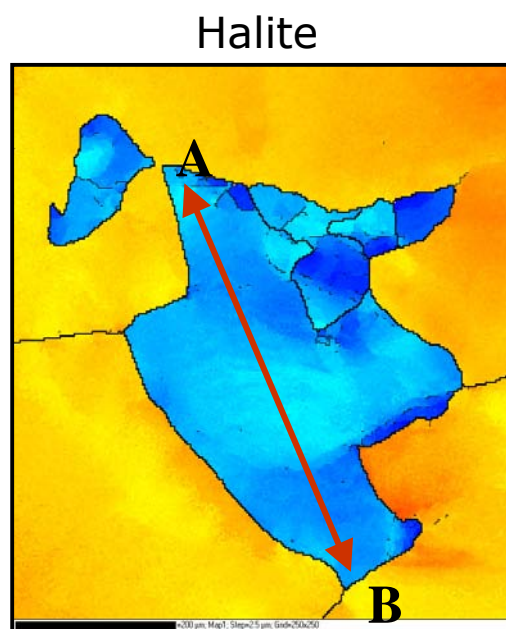
Deformed



Plastic strain manifested at least in part as ordered dislocation arrays can cause semi-continuous lattice rotation within a grain. This "intragranular misorientation" is measurable. Random or disordered dislocations only result in pattern quality degradation



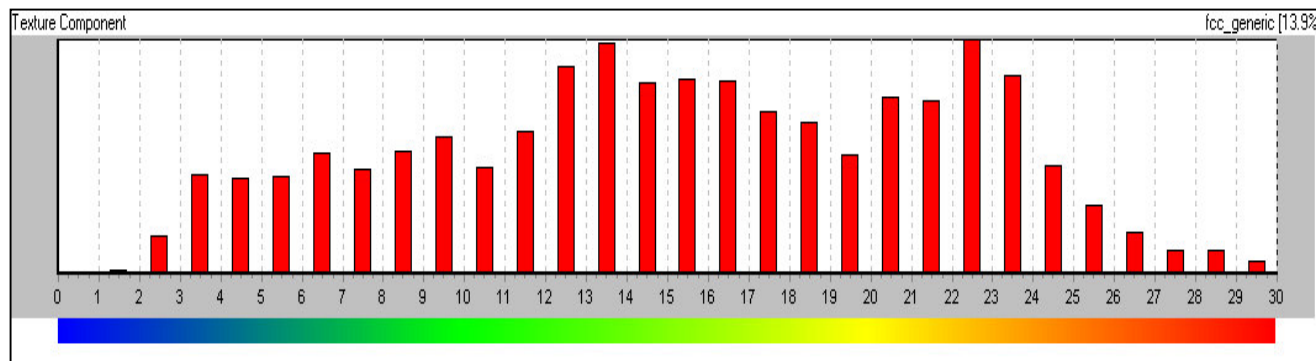
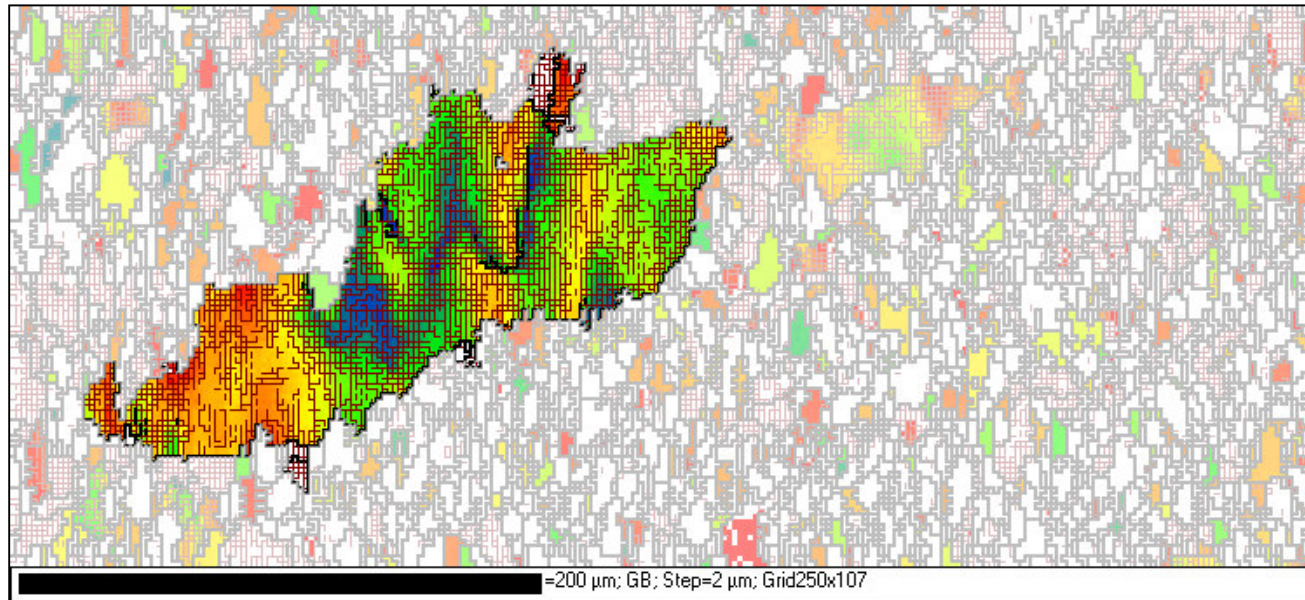
# Analysis of Strain - Intra Grain Misorientation



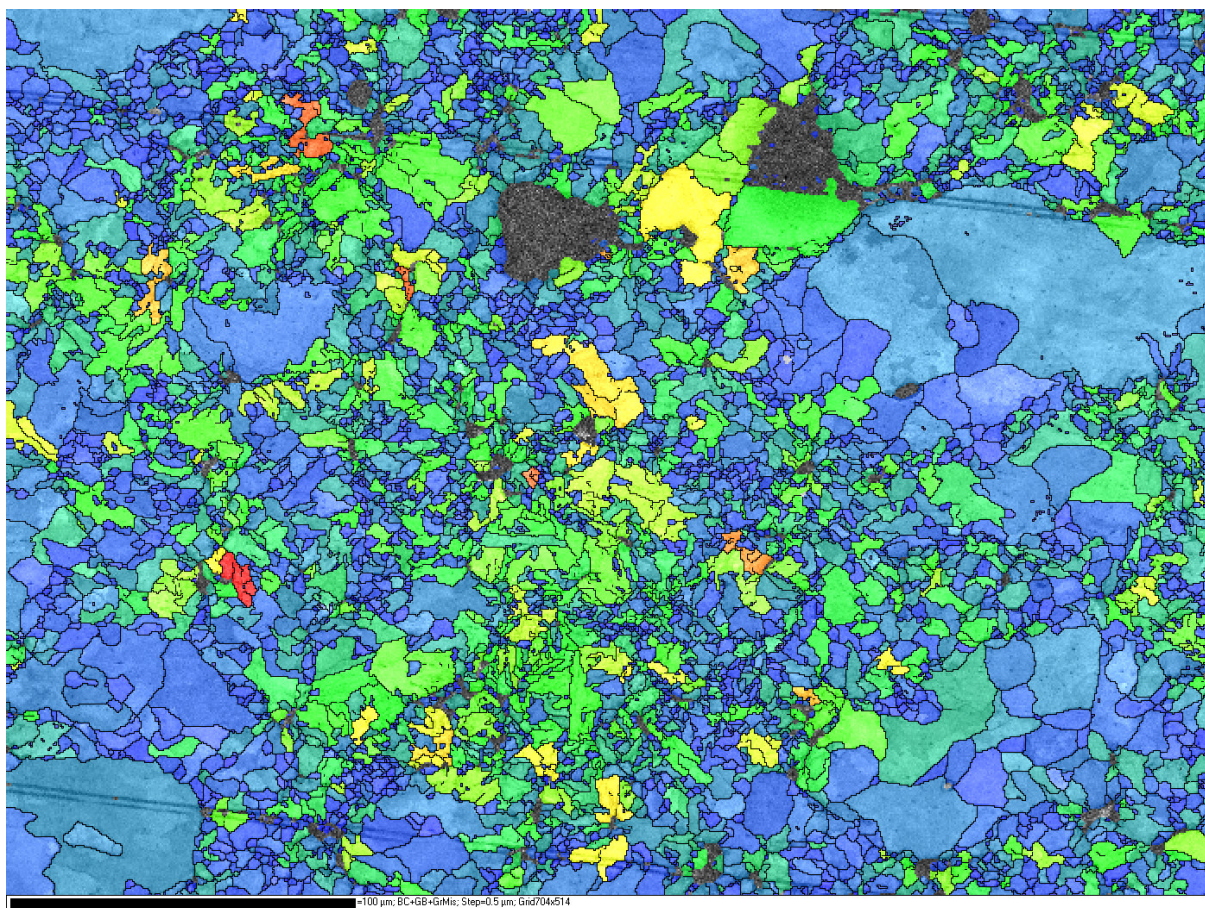


# Analysis of strain

Deformation-induced misorientation within large grain in Ni-base superalloy



# Analysis of strain

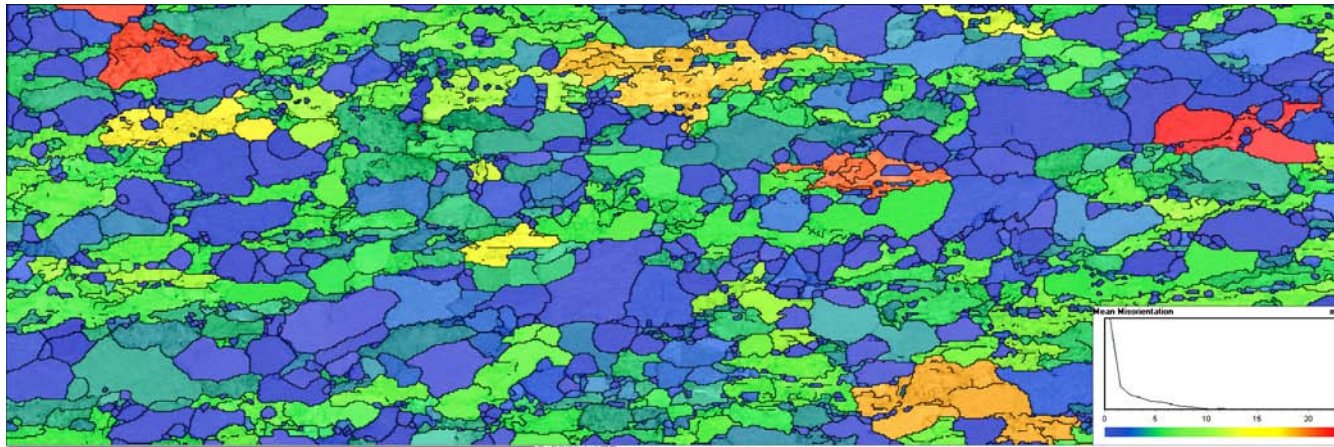


copper

- Isolate grains by strain

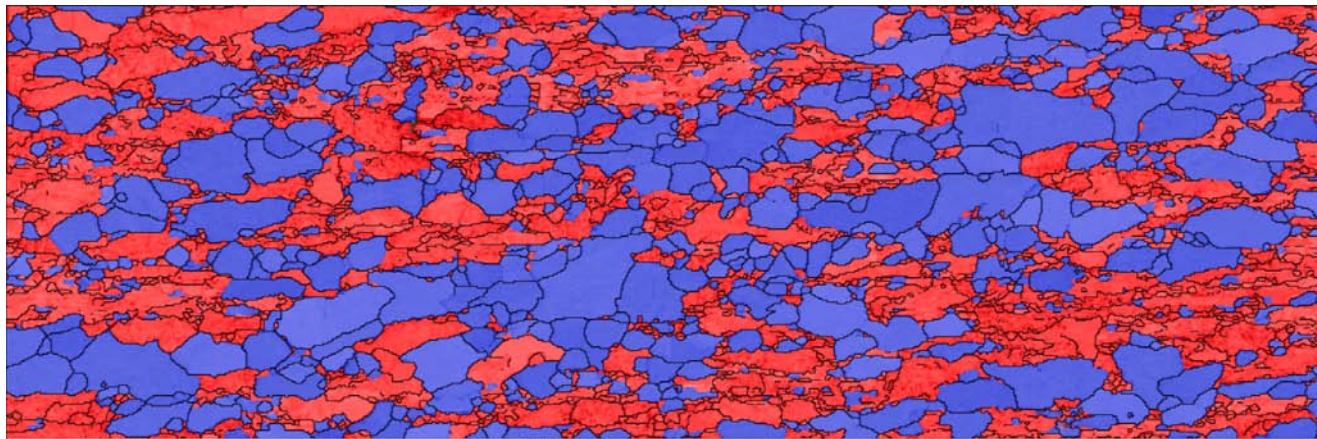


## Segmenting data by strain state - Recrystallisation



Rolled Mo  
Sheet

Strain (grain average misorientation) distribution map

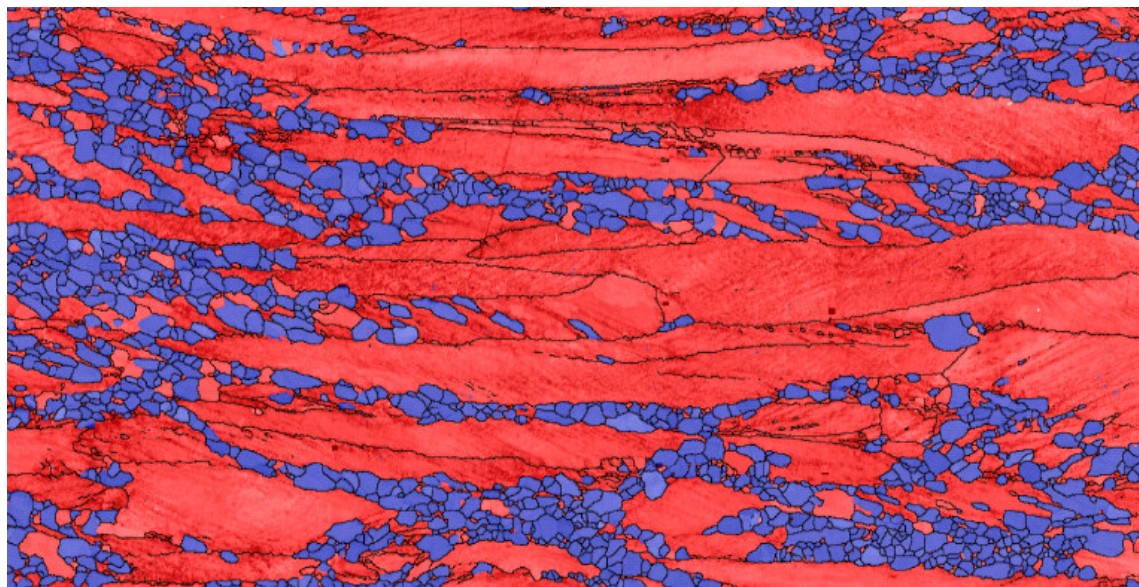


Red = deformed  
Blue = Recrystallized

Strain (grain average misorientation) classification map



# Segmenting data by strain state - Recrystallisation

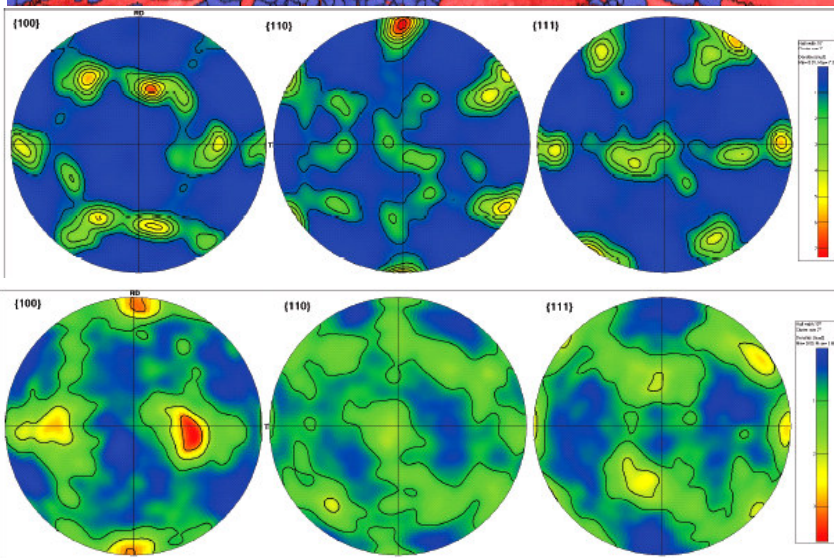


Rolling & heat treatment of Fe-Al binary alloy resulted in a partly deformed, partly recrystallized microstructure

Grains subgrouped by residual strain state:

Red deformed, blue recrystallized

Texture 'partitioning' revealed

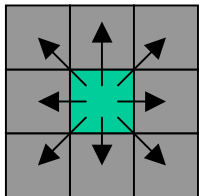
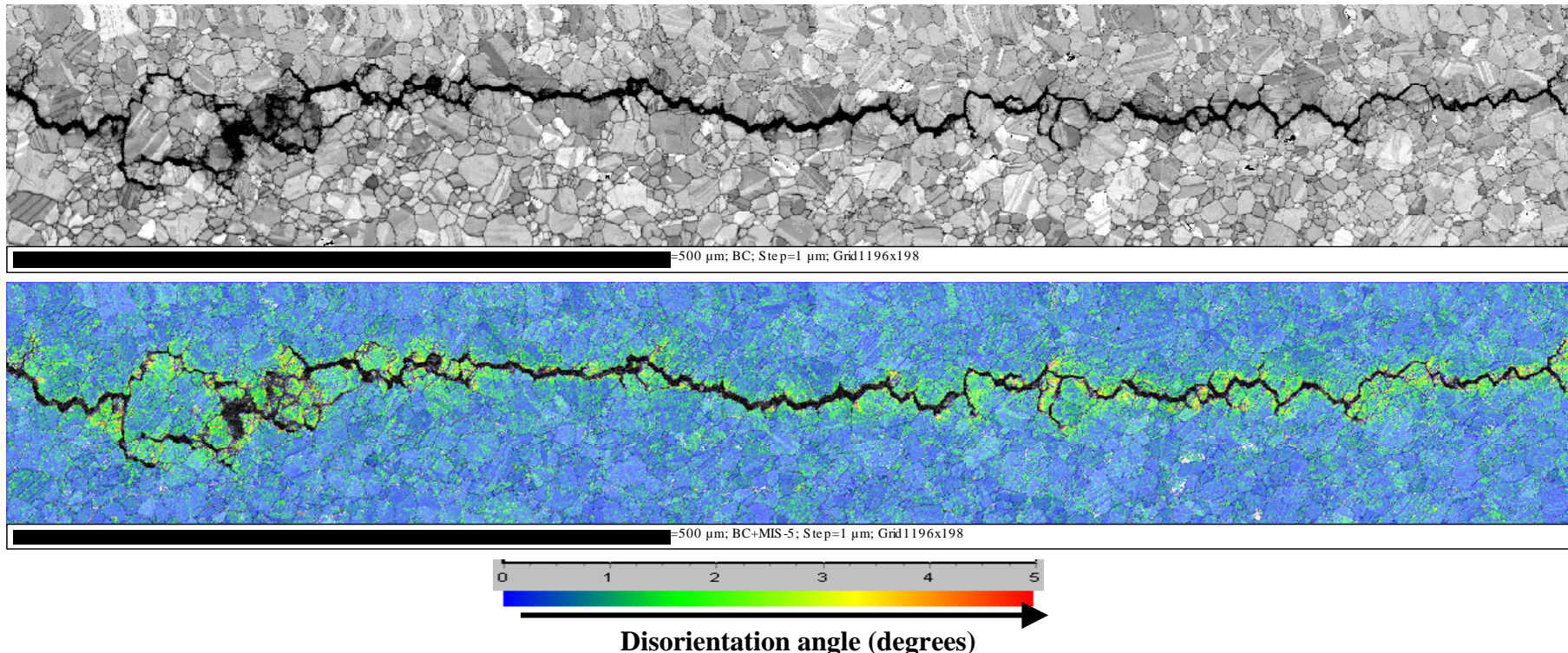


Deformed

Recrystallized



# Visualisation of strain



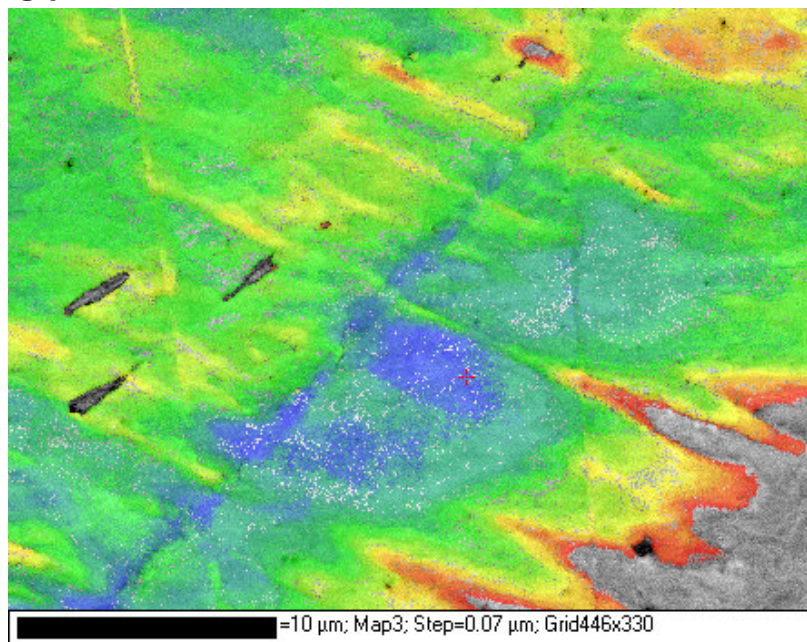
Each orientation is surrounded by 8 nearest neighbors.  
The disorientation is calculated through all of the 8 nearest neighbors to get an averaged value.

$$g_{ij} = \sum g_i \cdot g_j^{-1}$$

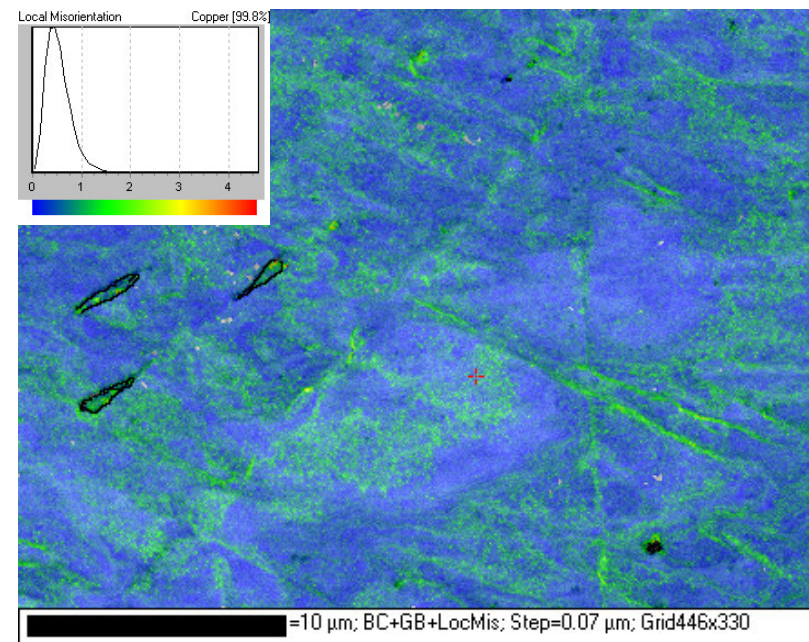


# Visualisation of Strain

Cu



Relative to selected  
reference point  
(cumulative rotation)

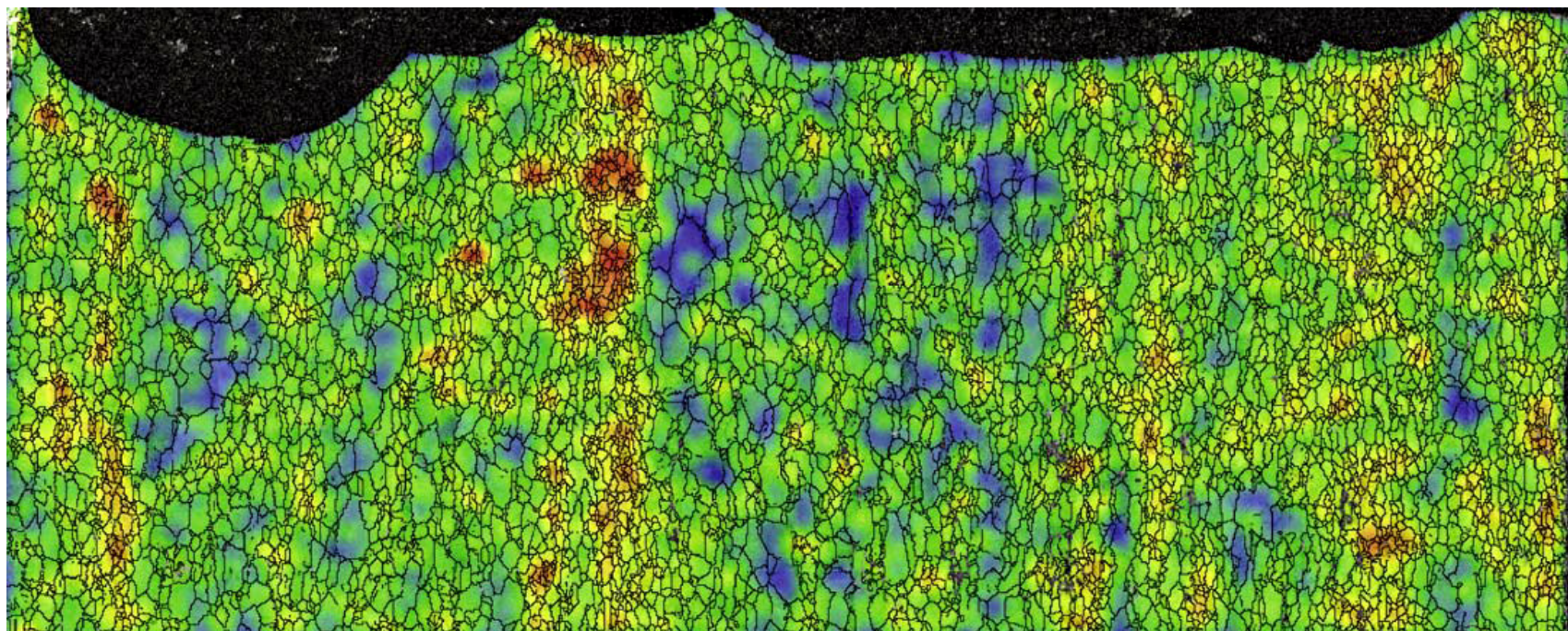


For each pixel, relative to  
surrounding pixels  
(local rotation)



# Visualisation of Strain

Ta sputter target



Strain localization + GB map

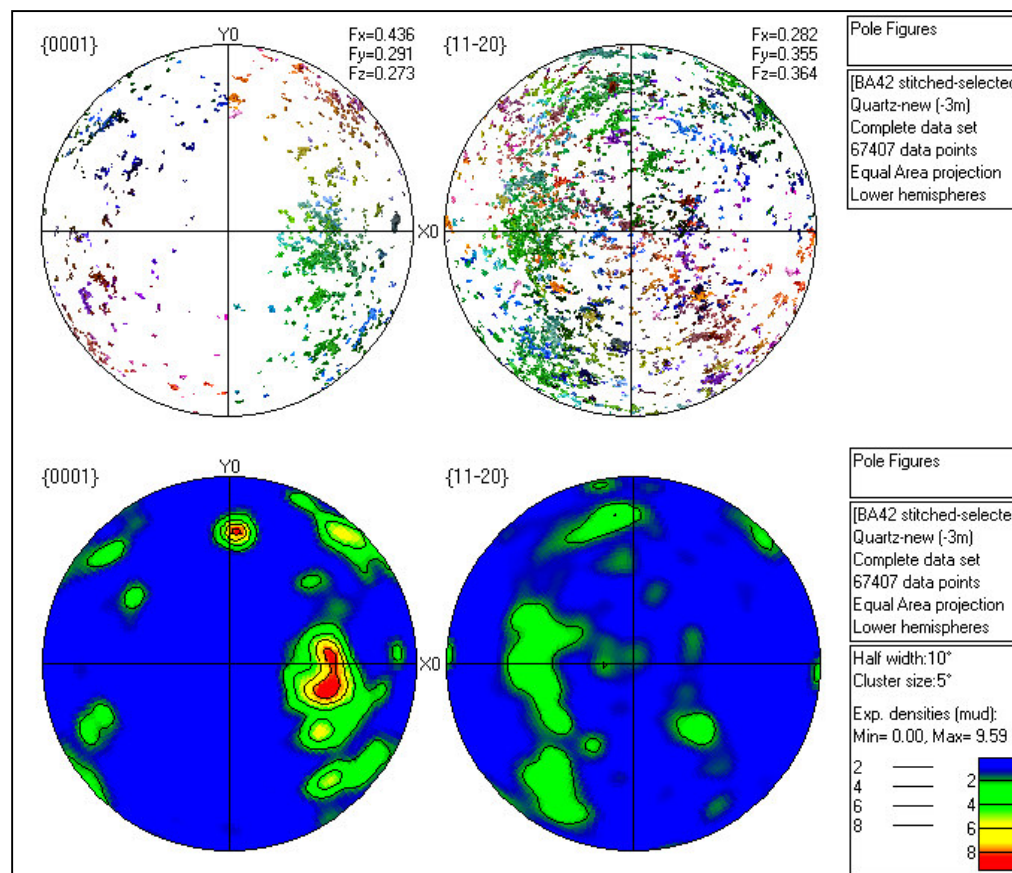
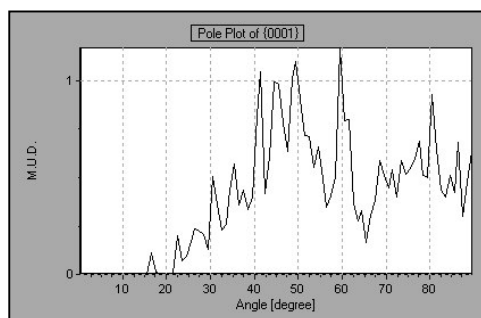
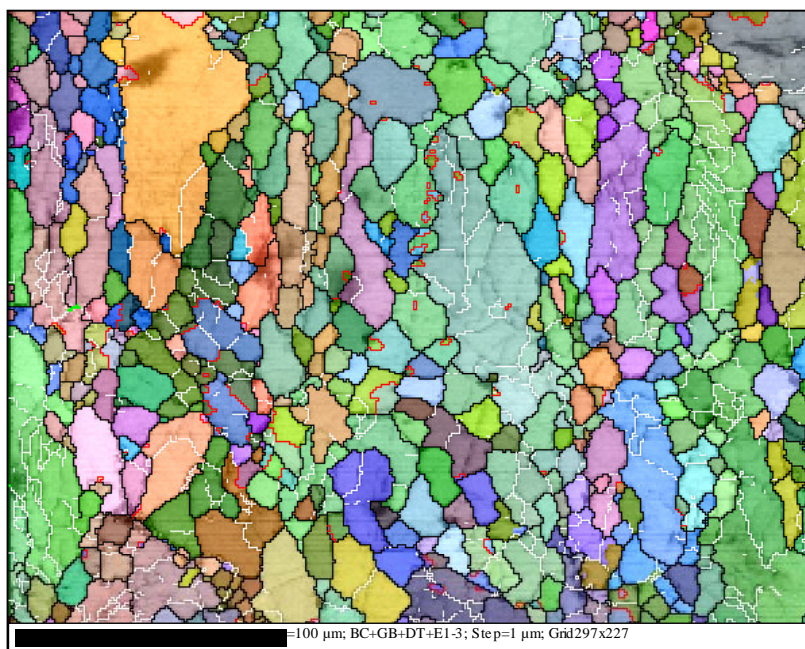
# Texture Analysis

Pole Figures  
Inverse Pole Figures  
ODF



# Texture Analysis: Pole Figures

Quartzite

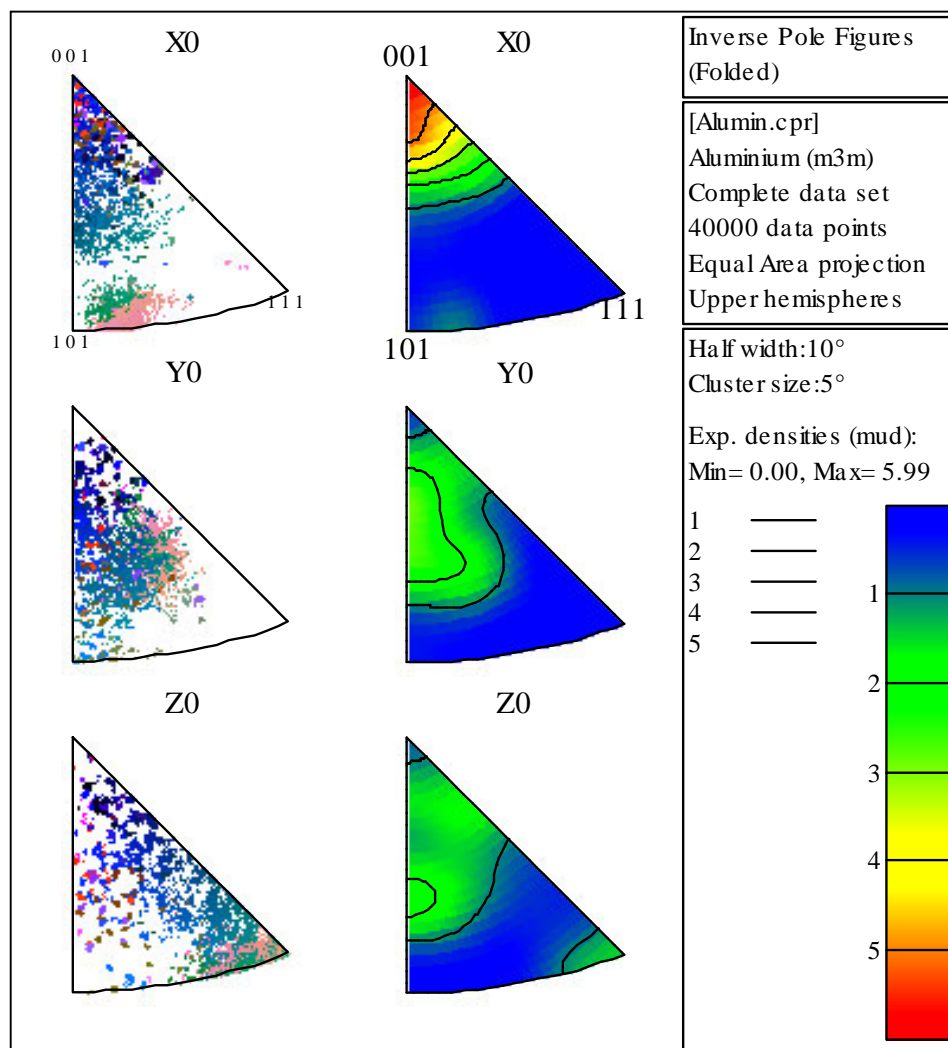
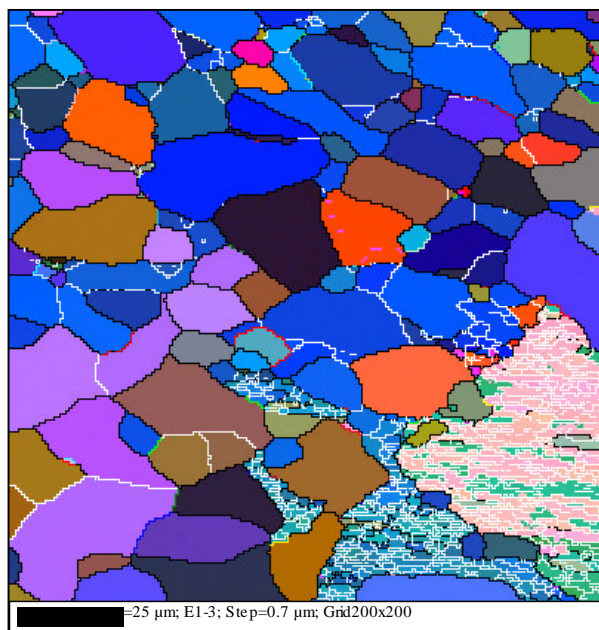


"Pole Plot" for {0001}

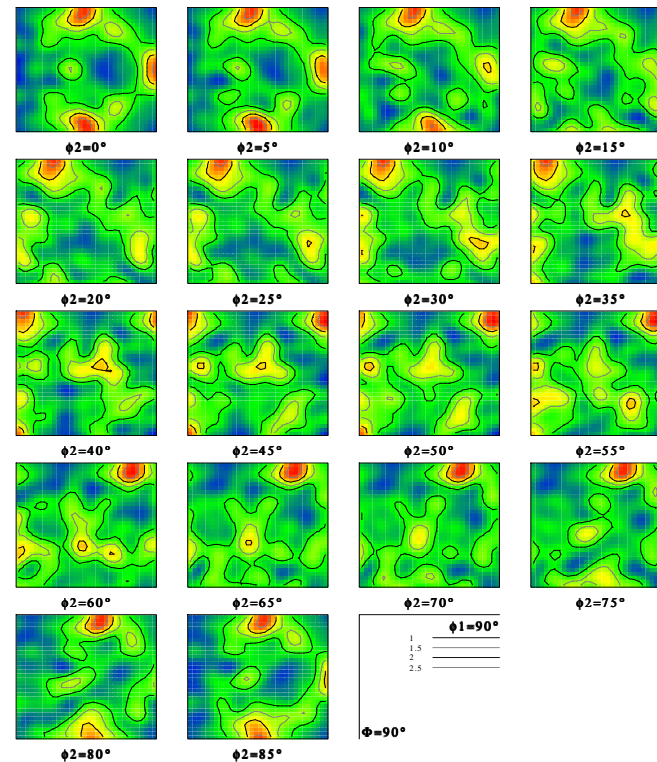
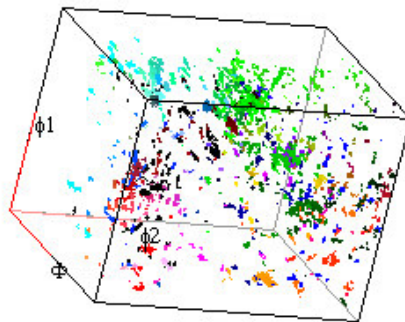
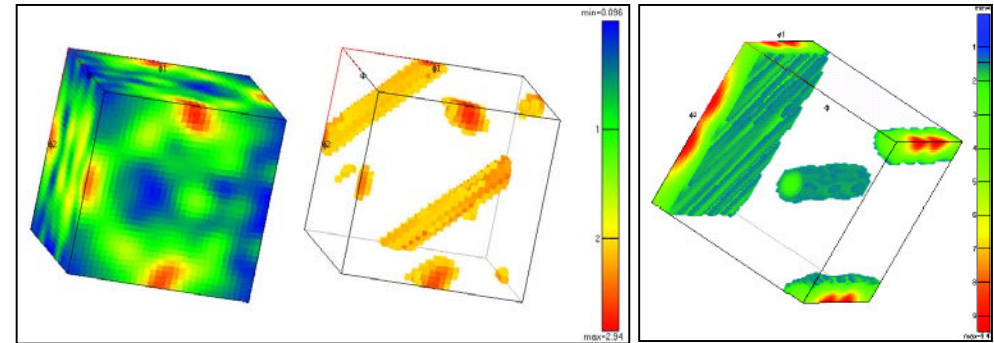
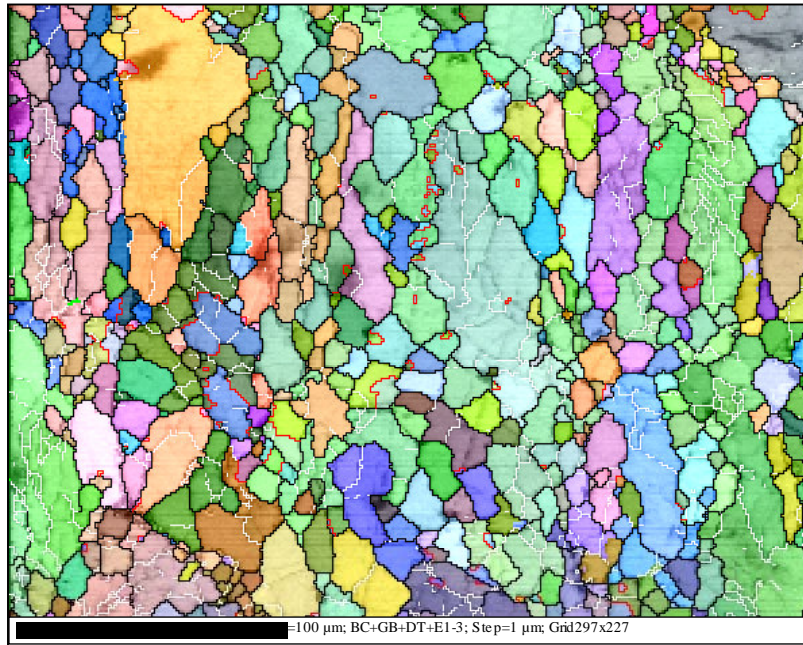


# Texture Analysis: Inverse Pole Figures

Rolled Al



## Texture Analysis: Orientation Distribution Functions (ODF)



Thank you